

IRIS

(Institute for Rare Isotope Science)

SRF Cavities

윤준영 연구위원

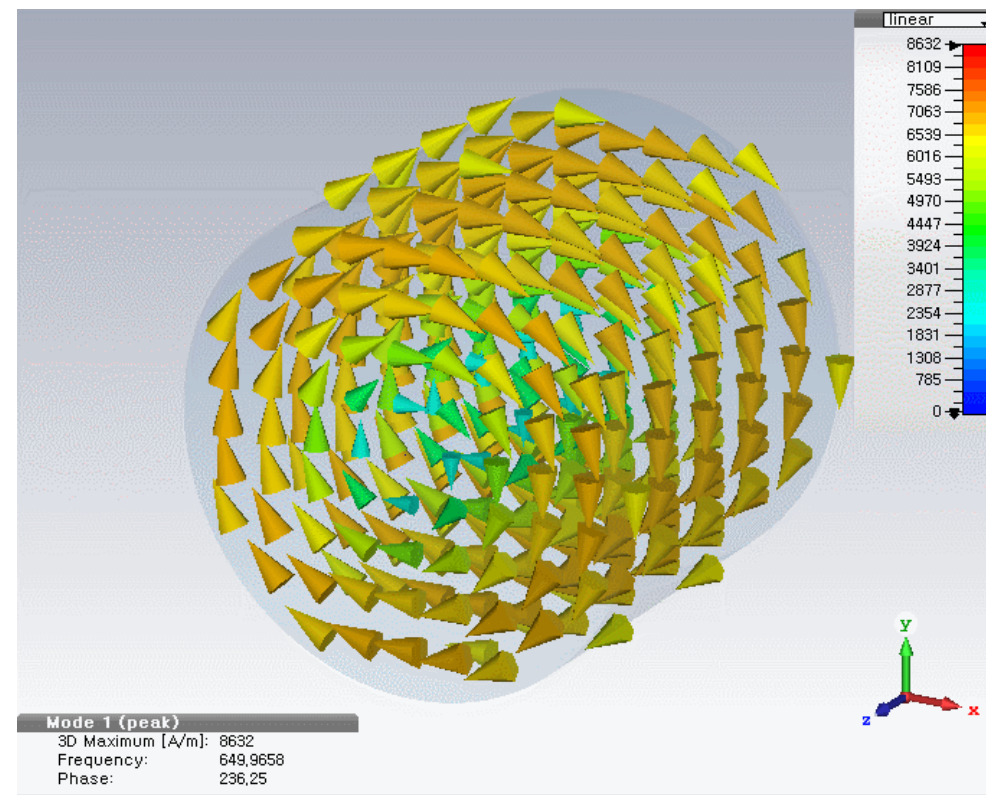
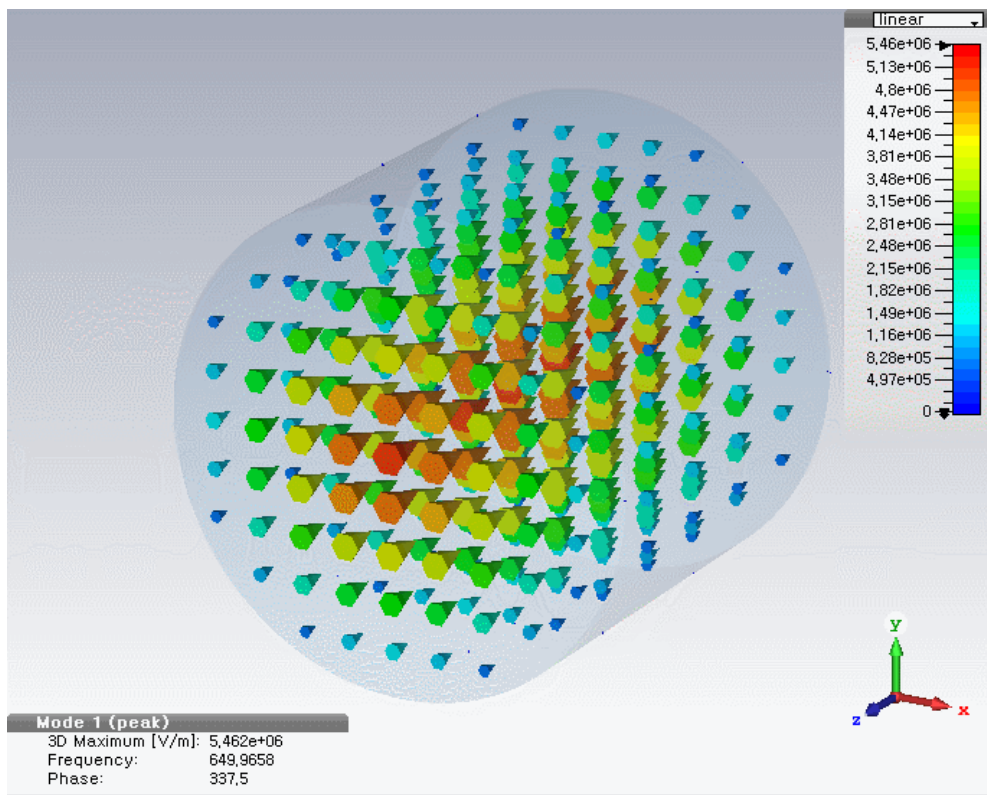
중이온가속기연구소
고에너지가속장치개발실

IRIS: SRF Cavities



강의 목표

- 고주파 시스템에 대한 이해 → Eiji Kako, "Fundamental of SRF Cavity System"
- 중이온가속기연구소에서 연구중인 초전도 가속관에 대한 이해



- 목 차 -

01 개요

- RF(Radio Frequency)란?

02 고주파 가속관

- 기초
- RAON 가속기 시스템 개요
- QWR, HWR 가속관 제작 및 활용 사례
- SSR1, SSR2 가속관 연구 현황

01 개요



■ 고주파(RF)란 무엇인가?

- 무선주파수(Radio Frequency)는 30 Hz ~ 300 GHz 범위의 전자기파

■ 전자기파

- 전자기파는 전기장과 자기장으로 이루어진 파동이다.
- 스코틀랜드의 물리학자 제임스 클러크 맥스웰(James Clerk Maxwell, 1831~1879)이 처음으로 전기와 자기현상을 통합
- 특정 조건에서 전기장이 자기장을 유도하고 자기장이 전기장을 유도하는 것을 맥스웰 방정식으로 정리함.

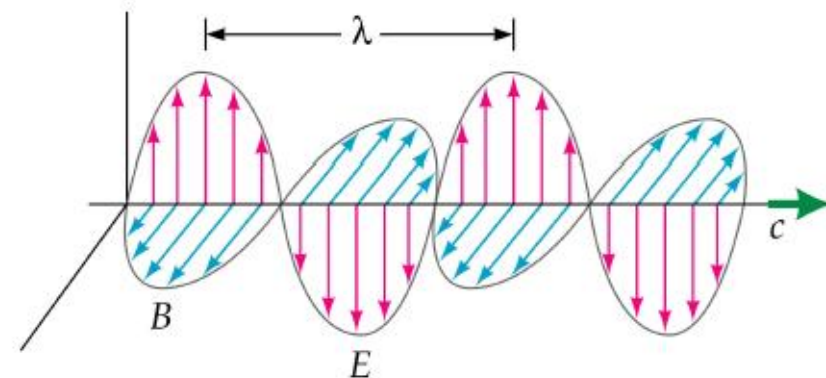


$\vec{E}$ = 전기장
 $\vec{H}$ = 자기장
 $\vec{D}$ = 전속밀도
 $\vec{J}$ = 전류

$$\left. \begin{aligned} \nabla \cdot \vec{D} &= \rho_V \\ \nabla \cdot \vec{B} &= 0 \\ \nabla \times \vec{E} &= -\frac{\partial \vec{B}}{\partial t} \\ \nabla \times \vec{H} &= \frac{\partial \vec{D}}{\partial t} + \vec{J} \end{aligned} \right\}$$

시간에 따라 변화하는 자기장은 전기장을 생성한다.

시간에 따라 변화하는 전기장은 자기장을 생성한다.

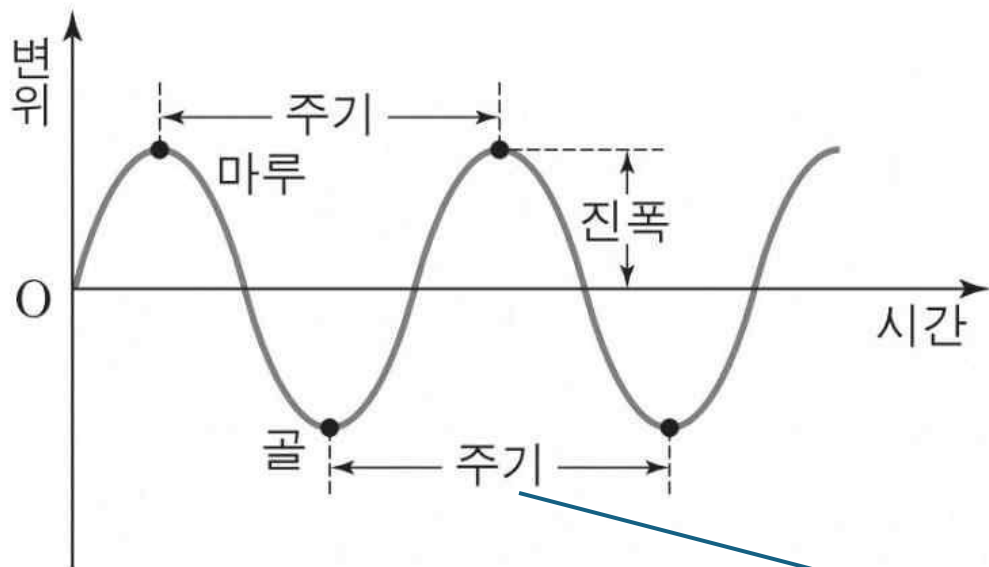


01 개요

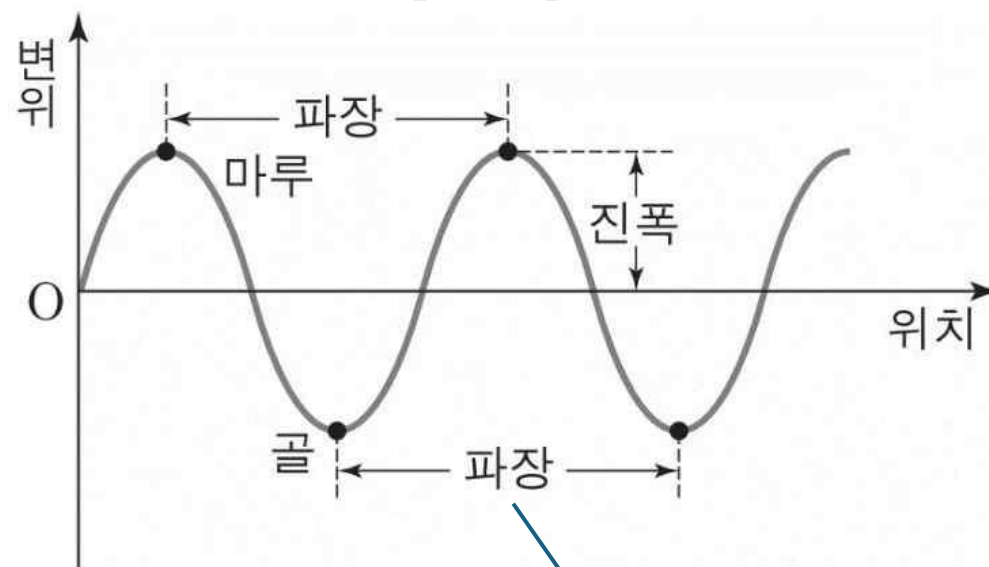


파동

파동의 주기



파동의 파장



$$T = \frac{1}{f}$$

$$v = \frac{\lambda}{T} = f\lambda$$

주기 = $\frac{1}{\text{진동수}}$

파동의 속도 = $\frac{\text{파장}}{\text{주기}} = \text{진동수} \times \text{파장}$

01 개요



■ 주파수 분류

명칭	주파수 대역	비고
HF (High Frequency)	3 ~ 30 MHz	-
VHF(Very High Frequency)	30 ~ 300 MHz	RAON ¹⁾ QWR(81.25 MHz) RAON HWR(162.5 MHz)
UHF(Ultra High Frequency)	0.3 ~ 1 GHz	RAON SSR1 & 2(325 MHz) PLS ²⁾ main RF cavity(500 MHz)
L band	1 ~ 2 GHz	TESLA ³⁾ 9-cell cavity(1.3 GHz) 4GSR ⁴⁾ 3 rd harmonic cavity(1.5 GHz)
S band	2 ~ 4 GHz	PLS Linac(2856 MHz)
C band	4 ~ 8 GHz	-
X band	8 ~ 12 GHz	CLIC ⁵⁾ (12 GHz)

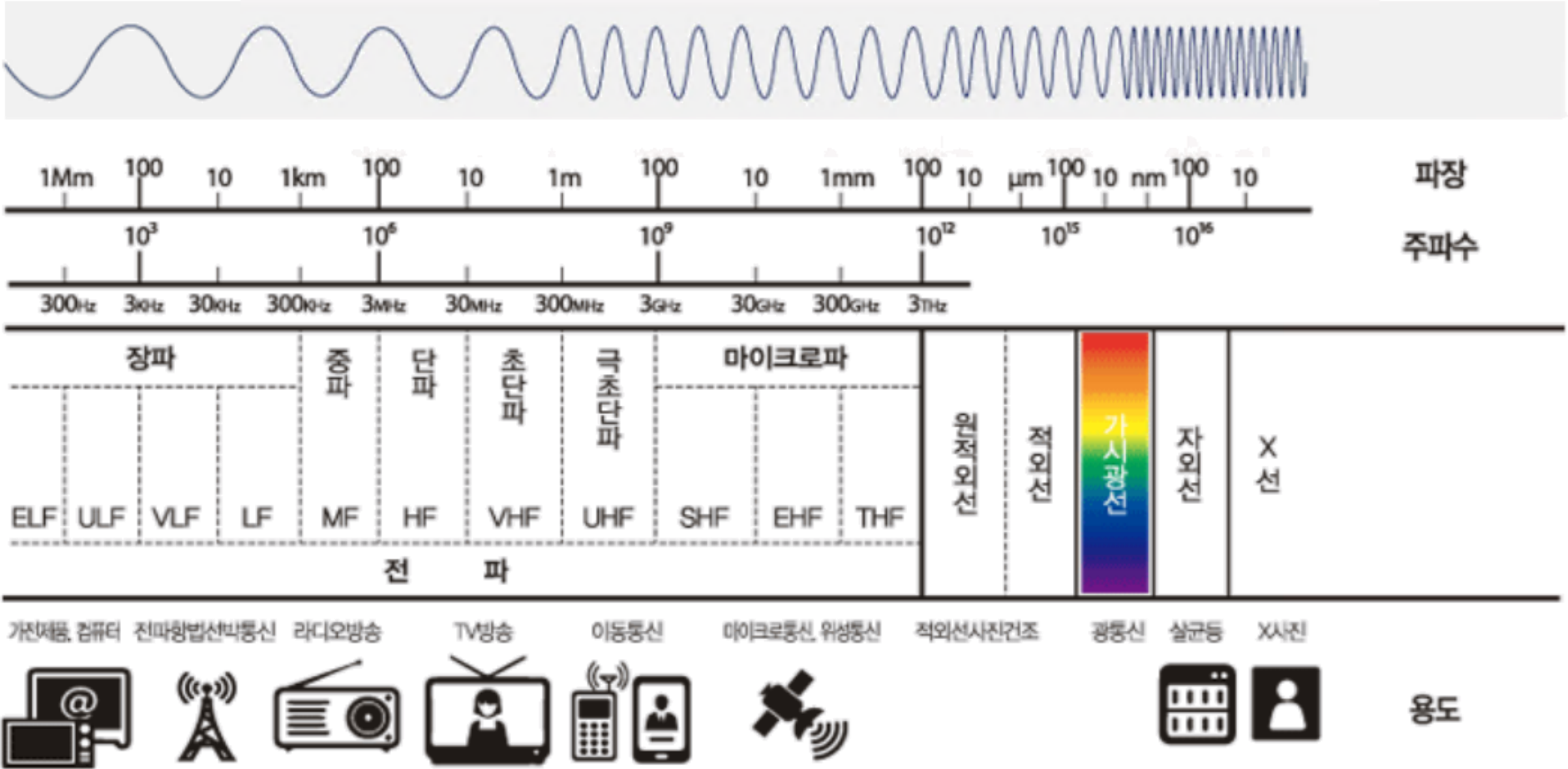
출처: IEEE 521-2002, IEEE Standard Letter Designations for Radar-Frequency Bands

- 1) RAON: Rare isotope Accelerator complex for ON-line experiments
- 2) PLS: Pohang Light Source
- 3) TESLA: linear electron-positron collider, DESY, Germany
- 4) 4GSR: 4th Generation Storage Ring
- 5) CLIC: Compact Linear Collider

01 개요



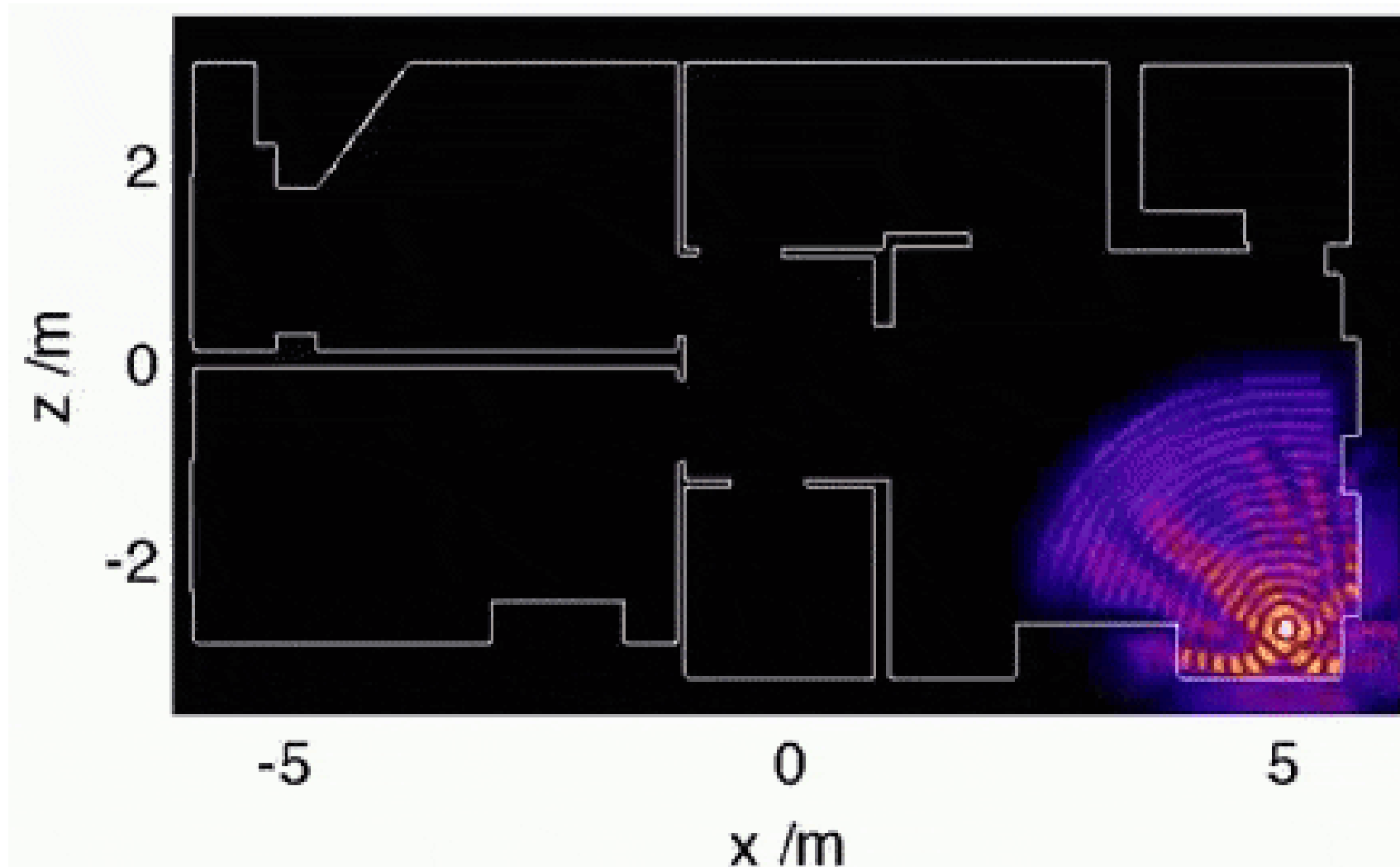
주파수 분류



01 개요



- WiFi



- 목 차 -

01 개요

- RF(Radio Frequency)란?

02 고주파 가속관

- 기초
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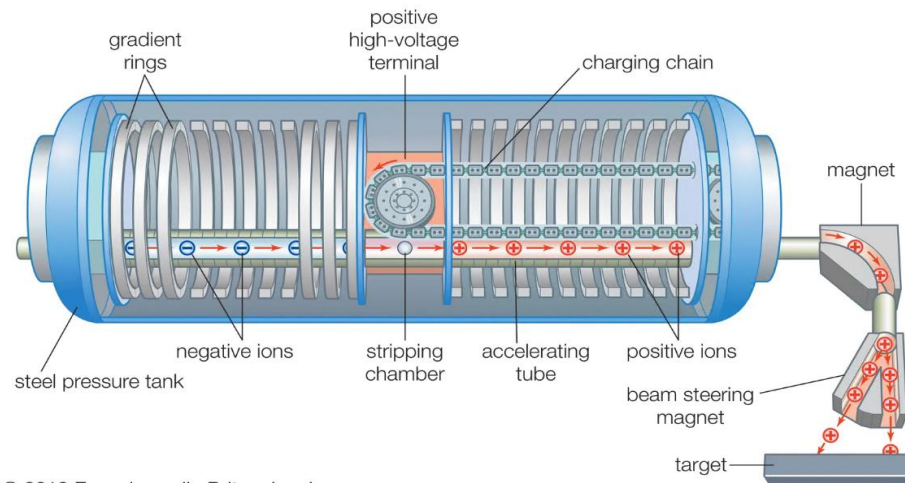
02 고주파 가속관



■ 기초: RF를 쓰는 이유

- 더 작은 cavity로 더 강한 가속 전압을 만들어 낼 수 있음.

정전형 가속기(Constant-voltage accelerator)



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← ~10 m →

< Two-stage tandem particle accelerator >

$$V_{\text{acc}} = 6 \text{ MV}_{\text{KIST Tandetron}}$$

RF cavity



0.5 m

< 1.3 GHz cavity (KEK) >

Course materials, ASSCA2022, February 11-20, 2022, Korea University, Sejong, Korea.

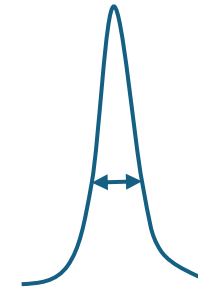
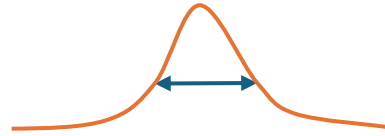
$$V_{\text{acc}} > 7 \text{ MV}_{\text{Nb}}$$

$$V_{\text{acc}} > 2.4 \text{ MV}_{\text{Cu}}$$

02 고주파 가속관



■ 기초: 상전도 vs 초전도



	상전도 가속관 (NC, Normal conducting)	초전도 가속관 (SC, Superconducting)
재질	OFHC, Cu, 무산소동	Nb, Niobium 또는 Nb-coated Cu
운전 온도	상온 (293 K)	2 ~ 4.5 K
운전 조건	Pulse 운전에 적합	CW, Continuous wave 가능
표면 저항	수 mΩ, RF 손실이 큼, 같은 조건에서 수십 kW	수 nΩ, RF 손실이 작음, 같은 조건에서 수 W
Q값 ($= \frac{\omega U}{P_{loss}}$)	$10^3 \sim 10^5$, 낮은 가속 효율	$10^9 \sim 10^{11}$, 높은 가속 효율
초기 구축 비용	낮음 (비교적 단순한 장비와 구조)	높음 (액체 헬륨 냉각 시설, 전송 시설 등) (복잡한 구조로 제작 비용과 난이도가 높음.)
운전	- RF 전력 손실로 인해 운전 비용이 비교적 높음. - 제작 비용이 저렴함. - 넓은 bandwidth로 외부 영향이 적음.	- RF 전력 손실이 적어 장기적으로 운전 비용이 낮음. - 운전 중 quench 관리 등 복잡함. - 좁은 bandwidth로 외부 진동에 취약

02 고주파 가속관



- 기초: 정전형 가속관 vs 고주파 가속관



폭포와 같음.



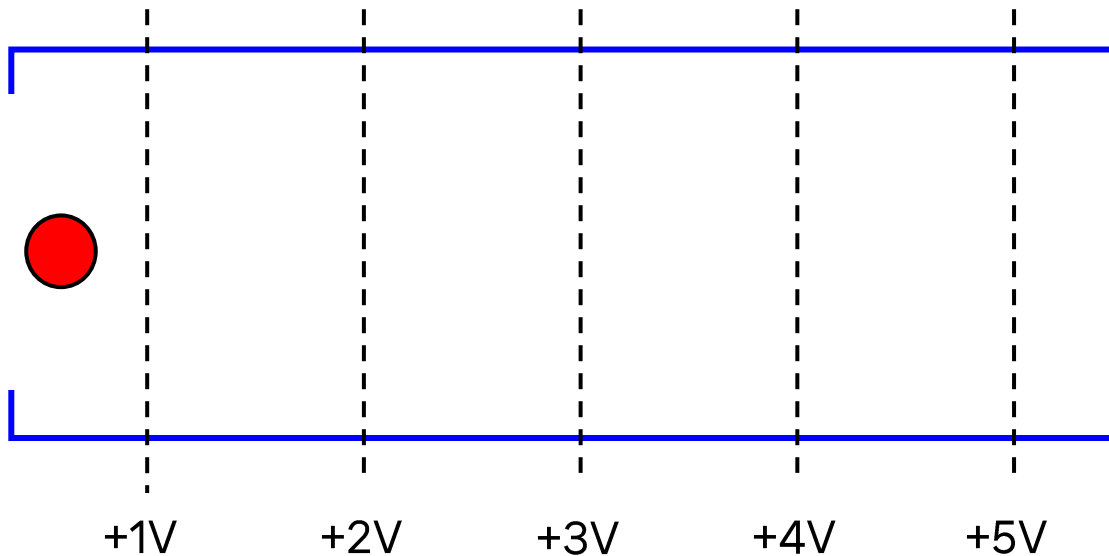
파도와 같음.

02 고주파 가속관

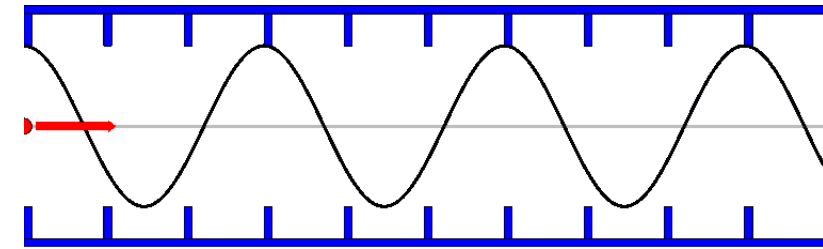


■ 기초: 정전형 가속관 vs 고주파 가속관

정전형 가속기(Constant-voltage accelerator)

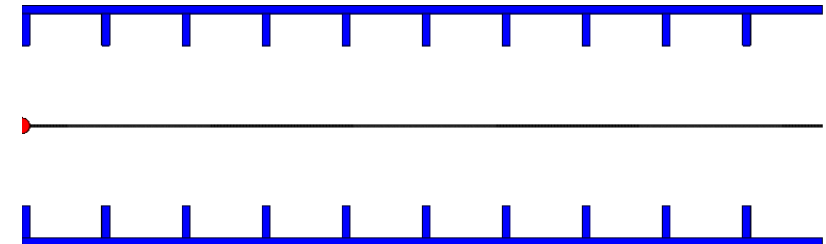


고주파 가속관(RF cavity)



< Traveling wave (TW) >

- 도파관의 길이가 길어짐.
- RF 전력 손실이 상대적으로 적음.



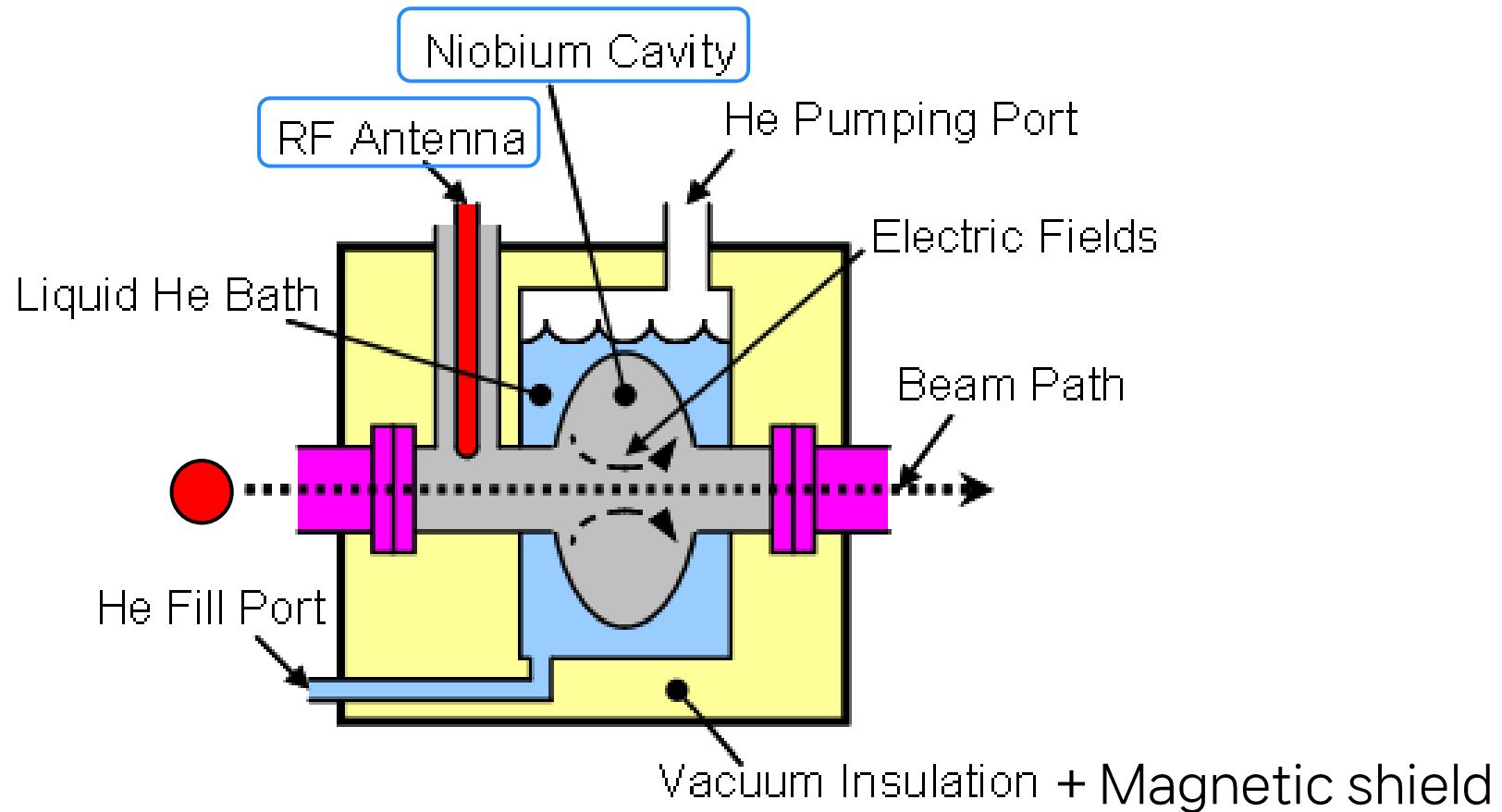
< Standing wave (SW) >

- 도파관의 길이가 짧아도 가능함.
- RF 전력 손실이 상대적으로 많음.

02 고주파 가속관



■ 기초: 초전도 가속관

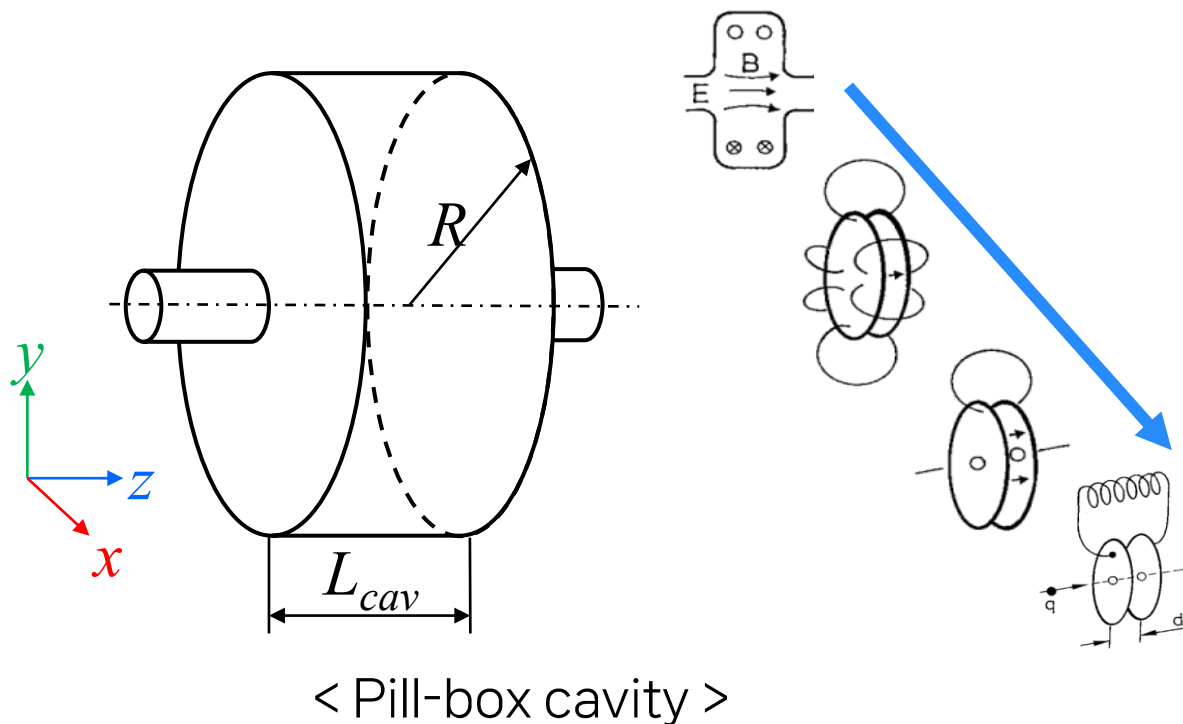


- 극저온(2 K or 4.5 K)에서 빔의 가속을 위해 운용하는 장치
- 고주파, 극저온, 초전도체, 진공 기술 등을 필요로 함.

02 고주파 가속관



■ 기초: 초전도 가속관의 크기 결정



- Cavity의 공진주파수는 반지름(R)에 의해 결정됨.
- Cavity의 길이는 cavity를 지나는 하전 입자의 속도에 의해 결정됨.

$$f_{TM010} = \frac{2.405c}{2\pi R} = \frac{1}{2\pi\sqrt{LC}}$$

< TM010 모드 공진 주파수 >

$$L_{cav} = \frac{\beta\lambda}{2}$$

< 입자의 속도(β)에 따른 cavity 길이 >

$$\vec{F} = q\vec{E} + q\vec{v} \times \vec{B}$$

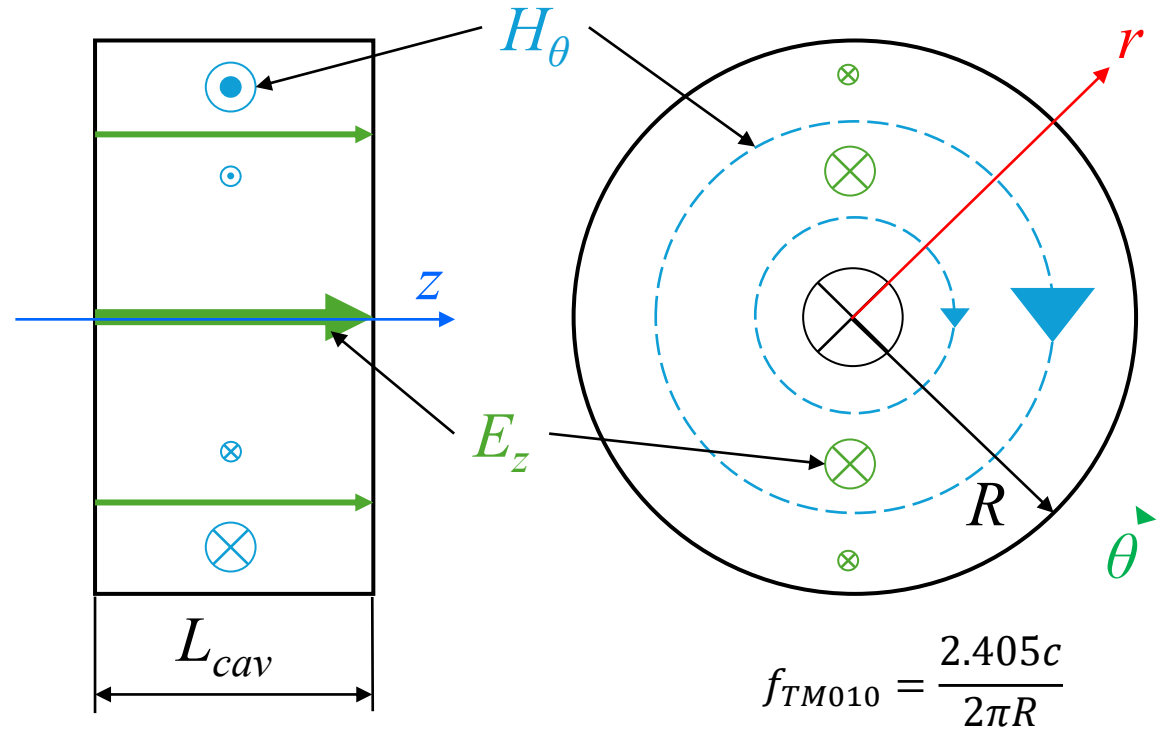
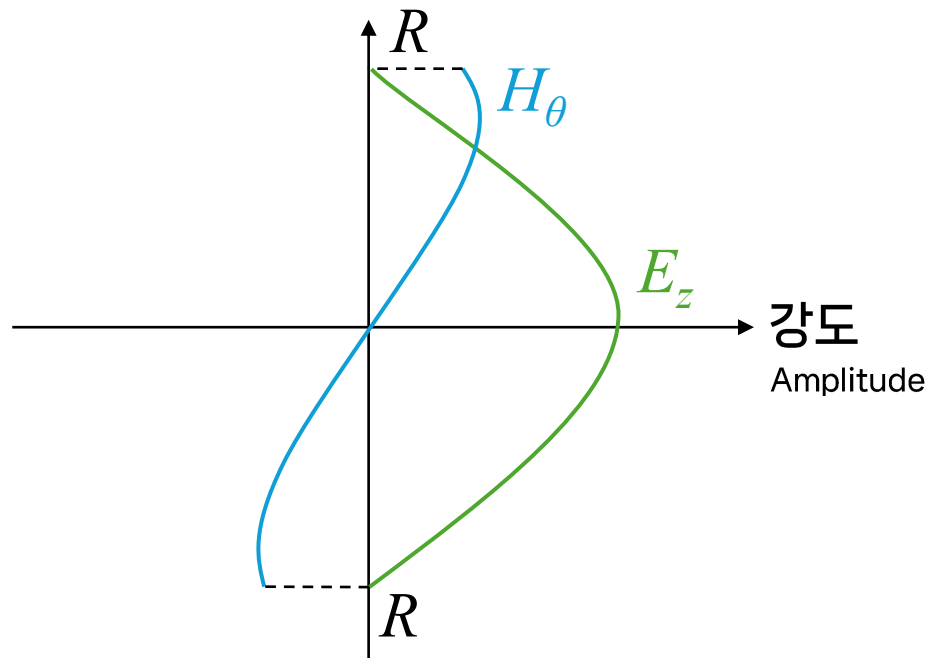
< Lorentz force >

02 고주파 가속관



■ 기초: 일반적인 초전도 가속관의 가속 모드 (TM₀₁₀)

$$E_z = E_0 J_0 \left(\frac{2.405r}{R} \right) e^{j\omega t} \quad H_\theta = -j \frac{E_0}{\sqrt{\mu/\epsilon}} J_1 \left(\frac{2.405r}{R} \right) e^{j\omega t}$$

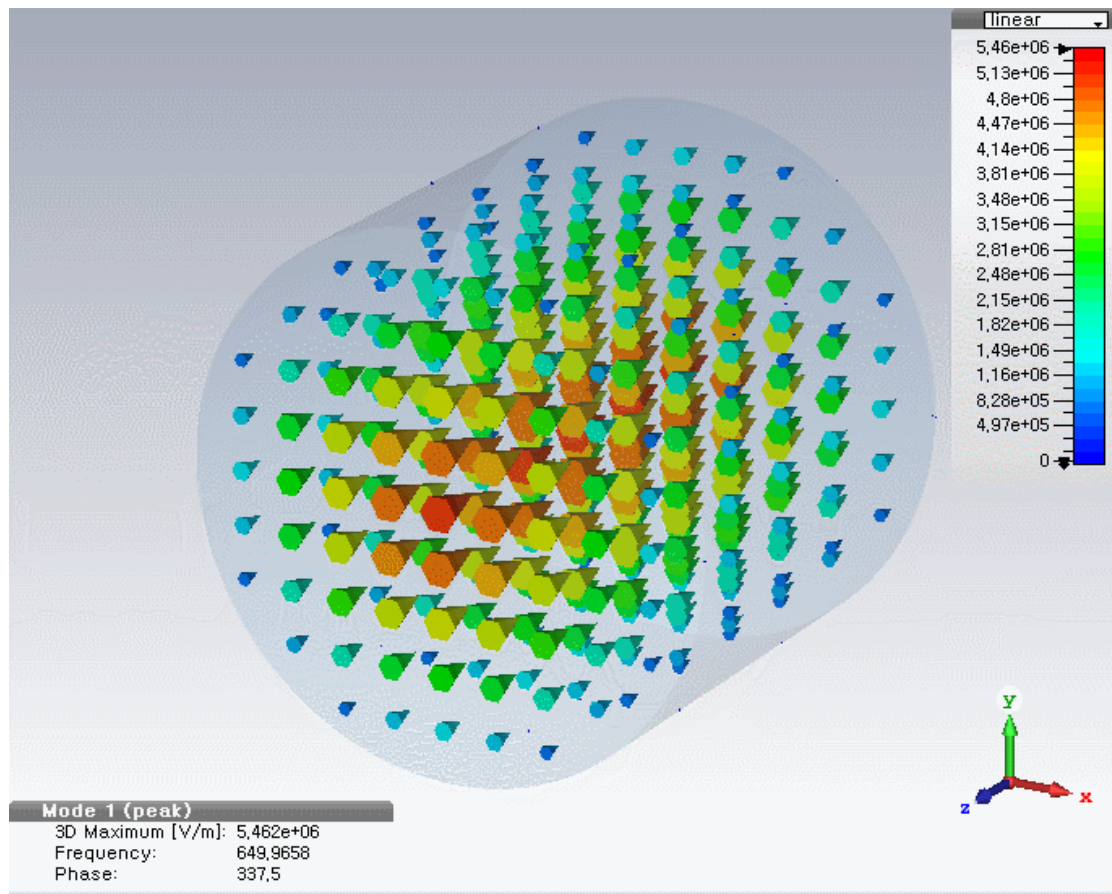


- 전기장은 $R = 0$ 인 지점에서 제일 강하여 하전 입자를 가속시킴.
- 자기장은 $R = \max$ 인 지점에서 제일 강하며 RF 손실(RF losses)를 일으킴.

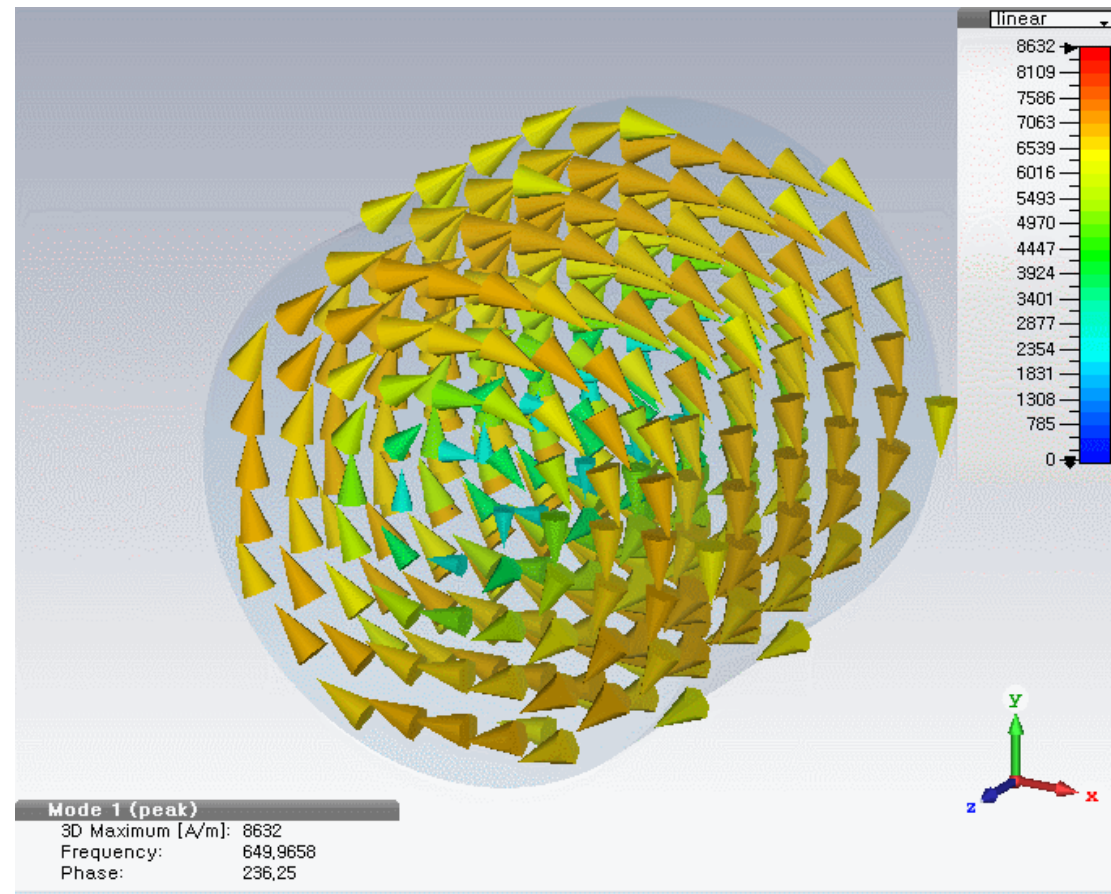
02 고주파 가속관



- 고주파 가속관의 가속 모드 (Fundamental mode, TM_{010})



< 전기장 공진 >



< 자기장 공진 >

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01 개요

- RF(Radio Frequency)란?

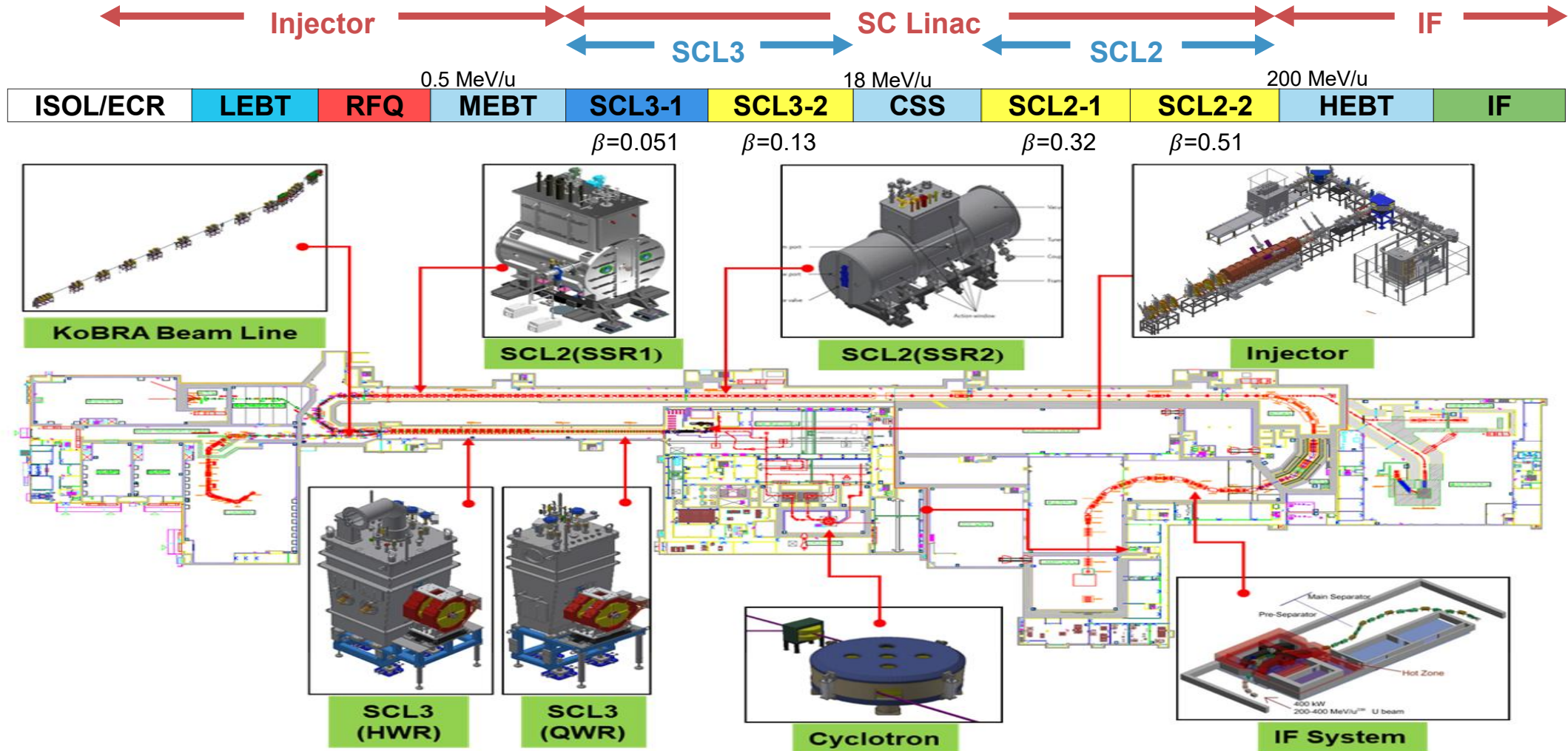
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02 고주파 가속관



- RAON Accelerator Systems → 정연세 연구위원, IRIS Overall

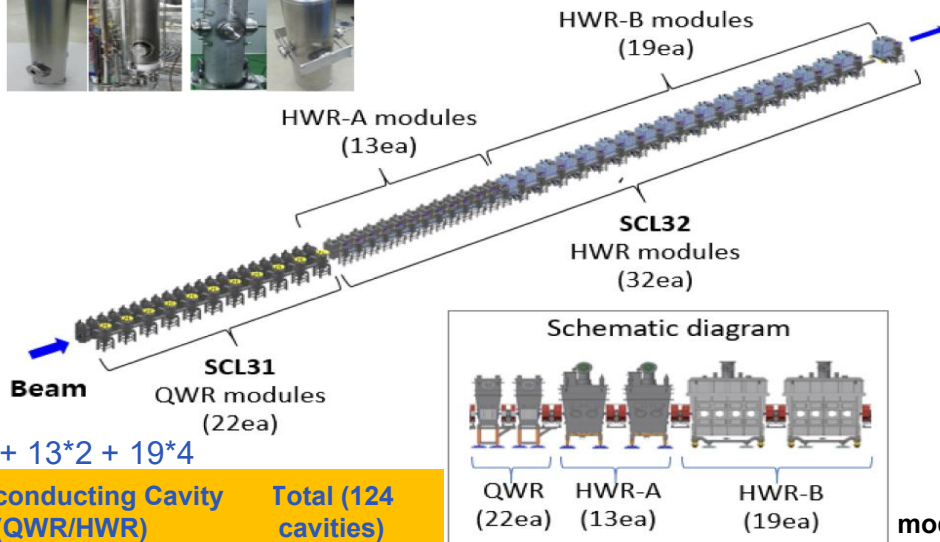


02 고주파 가속관



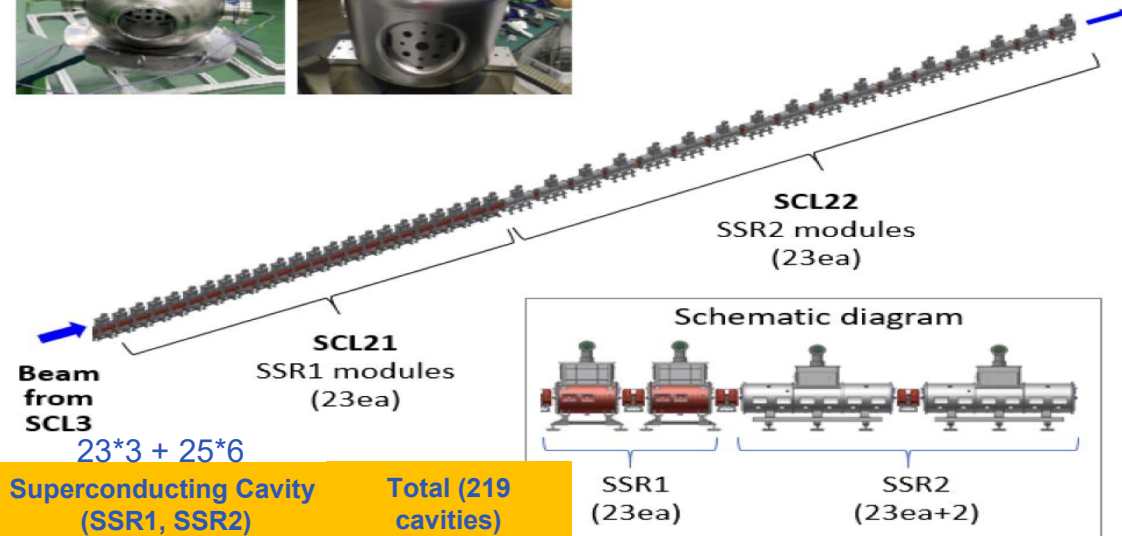
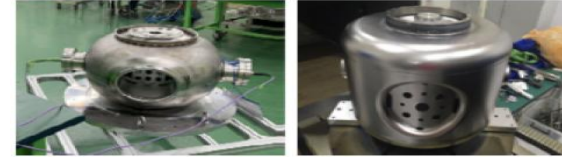
Superconducting Linear Accelerator

Superconducting Linac 3 (SCL3, Low-energy section)



선행 R&D

Superconducting Linac 2 (SCL2, High-energy section)



RF parameter

Type of cavity		Optimum β	f [MHz]	E_{pk}/E_{acc}	B_{pk}/E_{acc} [mT/MV/m]	E_{acc} [MV/m]	V_{acc} [MV]	QRs [Ω]
SCL3	QWR	0.051	81.25	6.0	10.8	5.7	1.07	18.1
	HWR	0.13	162.5	5.5	9.6	6.2	1.47	37.1
SCL2	SSR1	0.32	325	4.1	6.9	7.9	2.36	92.2
	SSR2	0.51	325	3.7	9.0	8.7	4.10	123.0

SCL2 beam parameter

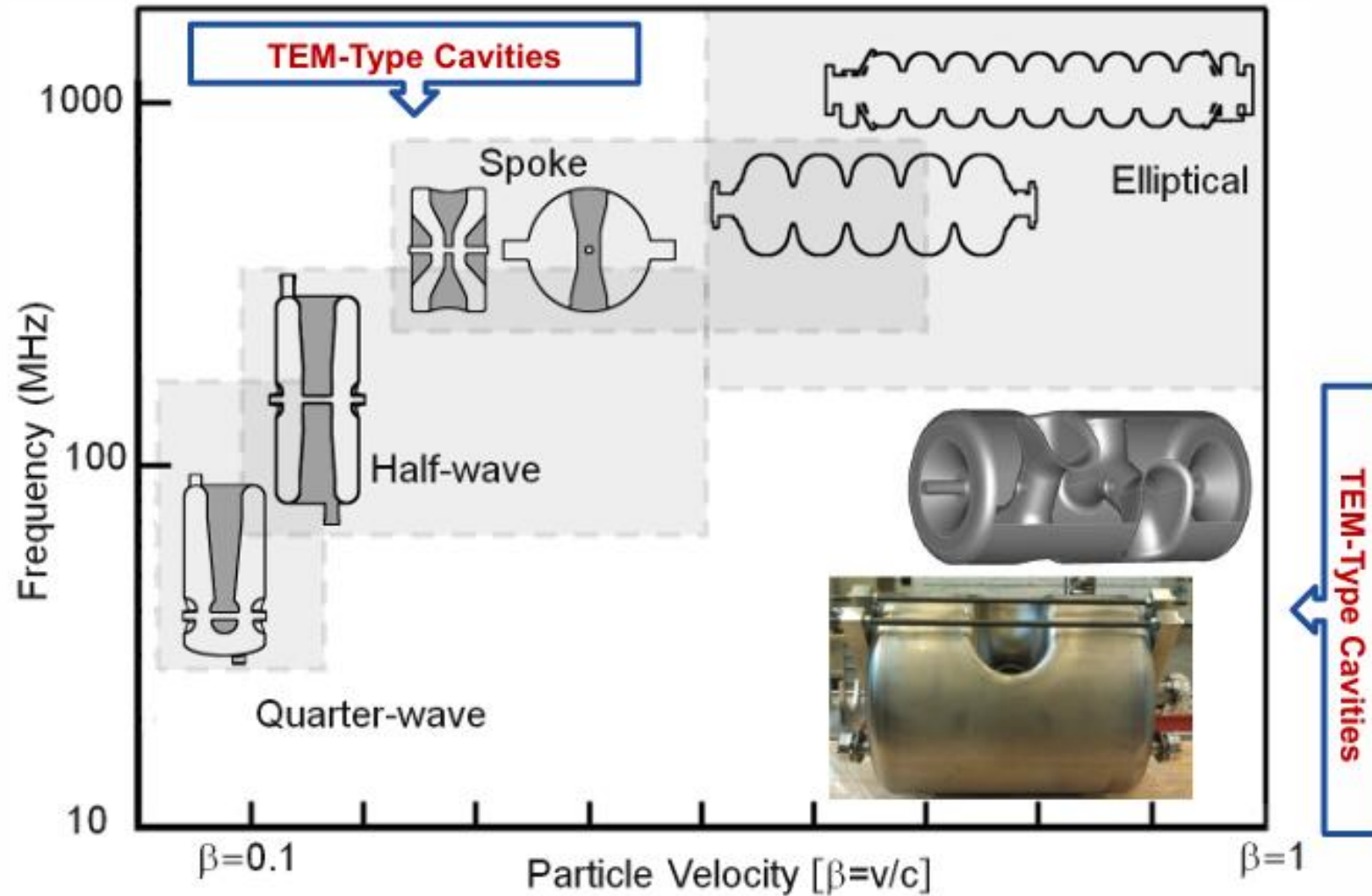
parameter \ Particle	Uranium	Proton
Energy [MeV/u]	200	600
Beam current [pμA]	8.3	660
Power (@ target) [kW]	400	400

02 고주파 가속관



■ TEM class Cavity

- 중이온가속기는 전자가속기와 달리 입자의 속도가 비교적 느려 TEM class 가속관을 활용하여 빔을 가속함.



02 고주파 가속관



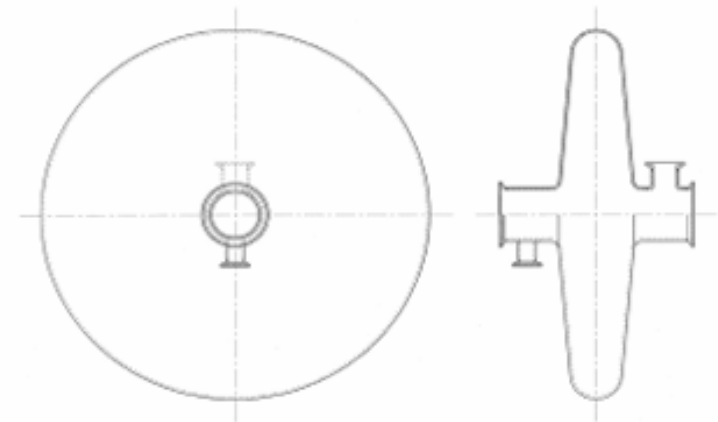
■ TEM class Cavity

- TEM-class cavity는 4.5 K 운용 가능성과 같은 주파수의 TM 가속관에 비해 크기가 작은 이점이 있음.

TM₀₁₀ Structures

Dia ~ 0.88 – 0.92 λ

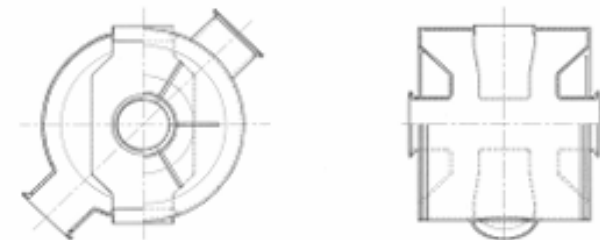
Coupling ~ 2%



$\lambda/2$ Structures

Dia~ 0.46 – 0.51 λ

Coupling ~ 20 - 30%



Example : 350 MHz, $\beta = 0.45$

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01 개요

- RF(Radio Frequency)란?

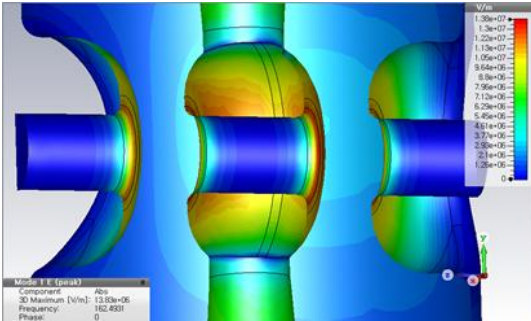
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02 고주파 가속관: HWR, 설계

Electromagnetic field analysis

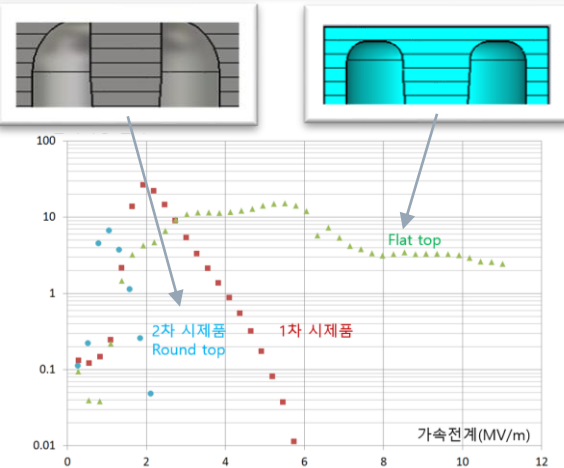
Beam port and beam sphere design



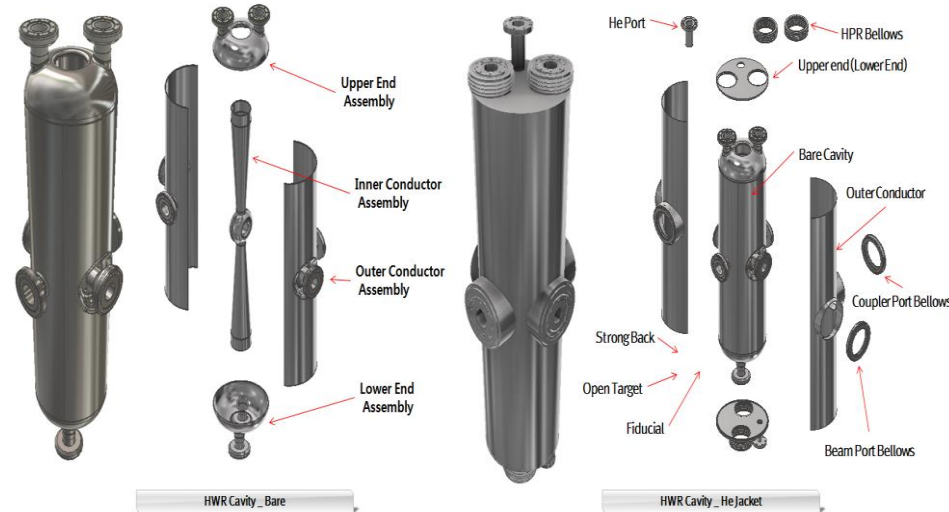
Minimize $E_{pk}/E_{acc} \rightarrow$ Suppress field emission

Minimize $B_{pk}/E_{acc} \rightarrow$ Enable higher operational gradient

Multipacting analysis

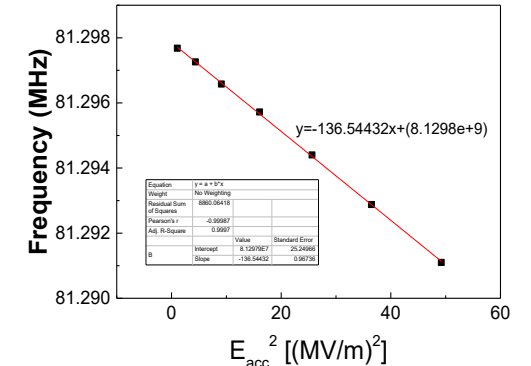


MP band below 2 MV/m



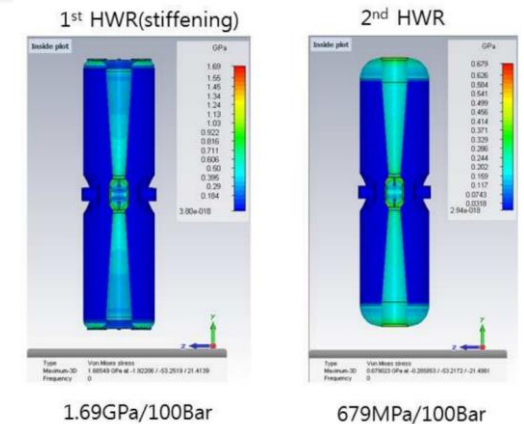
- Nb로만 구성된 Bare cavity
- 외부에 액체 헬륨을 담기 위한 He jacket

Lorentz force detuning (LFD)



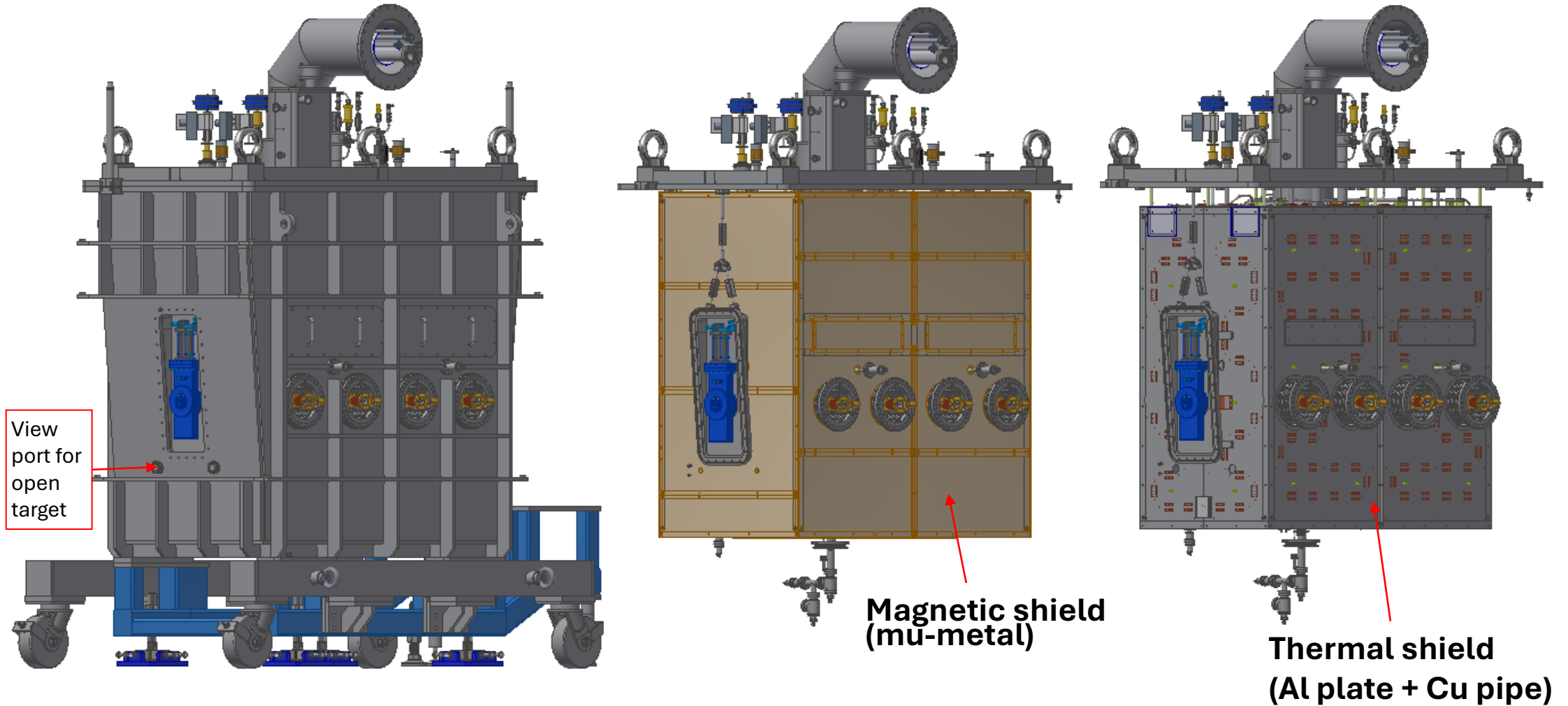
- For beam port free, $LFD_{cal} = -16.4 \text{ Hz} / (\text{MV/m})^2$
- For beam port free, $LFD_{Meas} = -14.7 \sim -44.6 \text{ Hz} / (\text{MV/m})^2$

Structure analysis

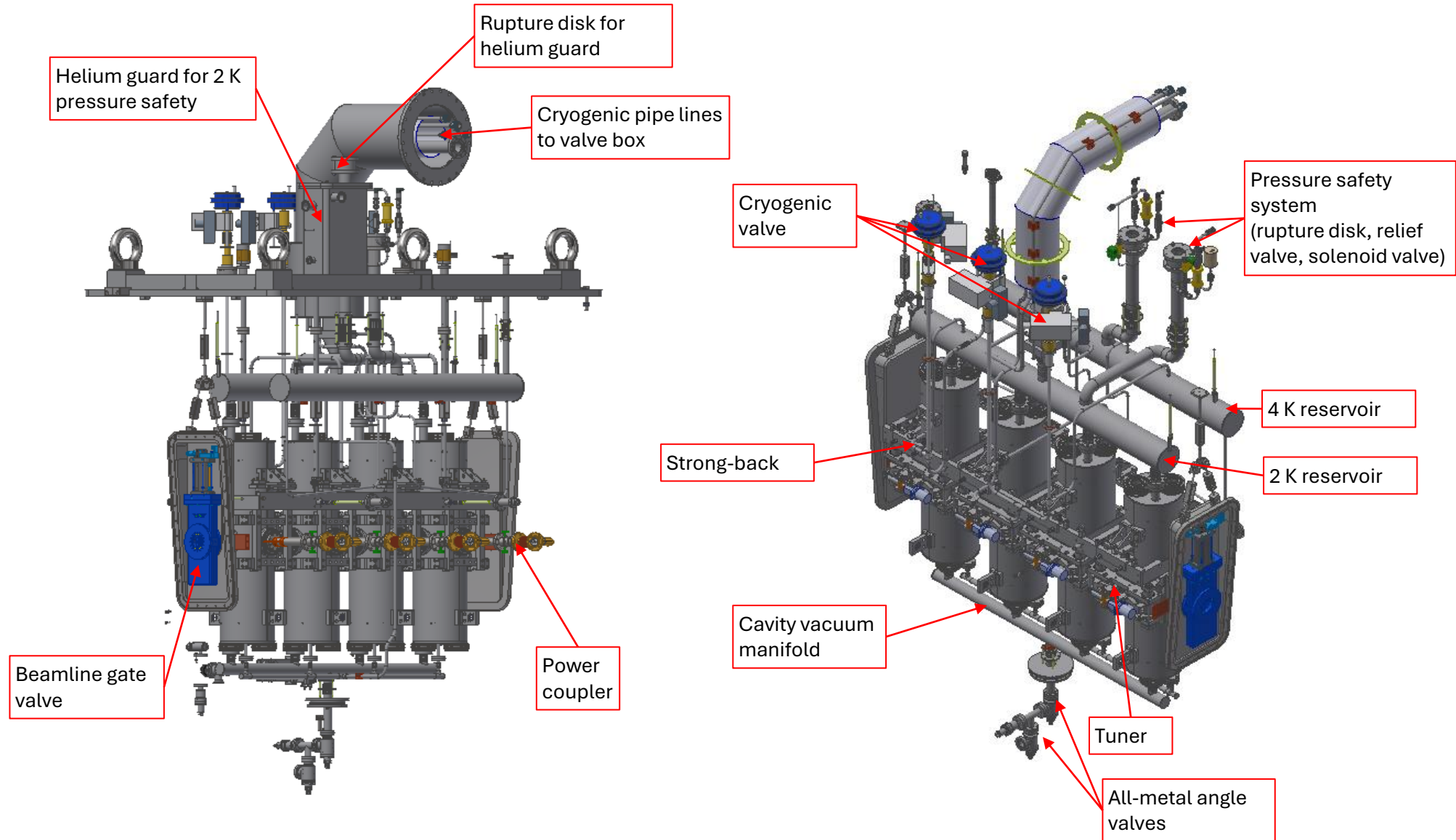


- Max. deformation: 1.9 mm $\rightarrow$ 0.86 mm
- Max. stress: 1.69 GPa $\rightarrow$ 679 MPa

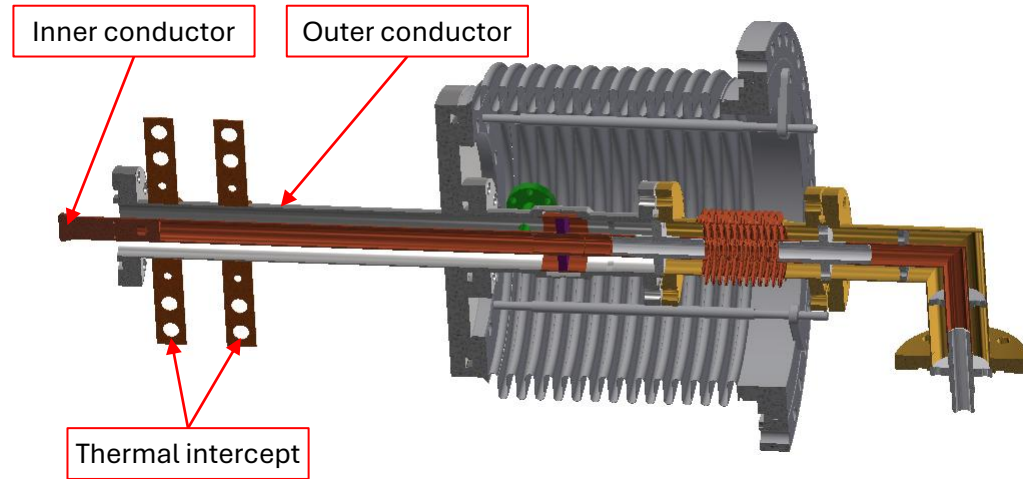
02 고주파 가속관: HWR 가속모듈



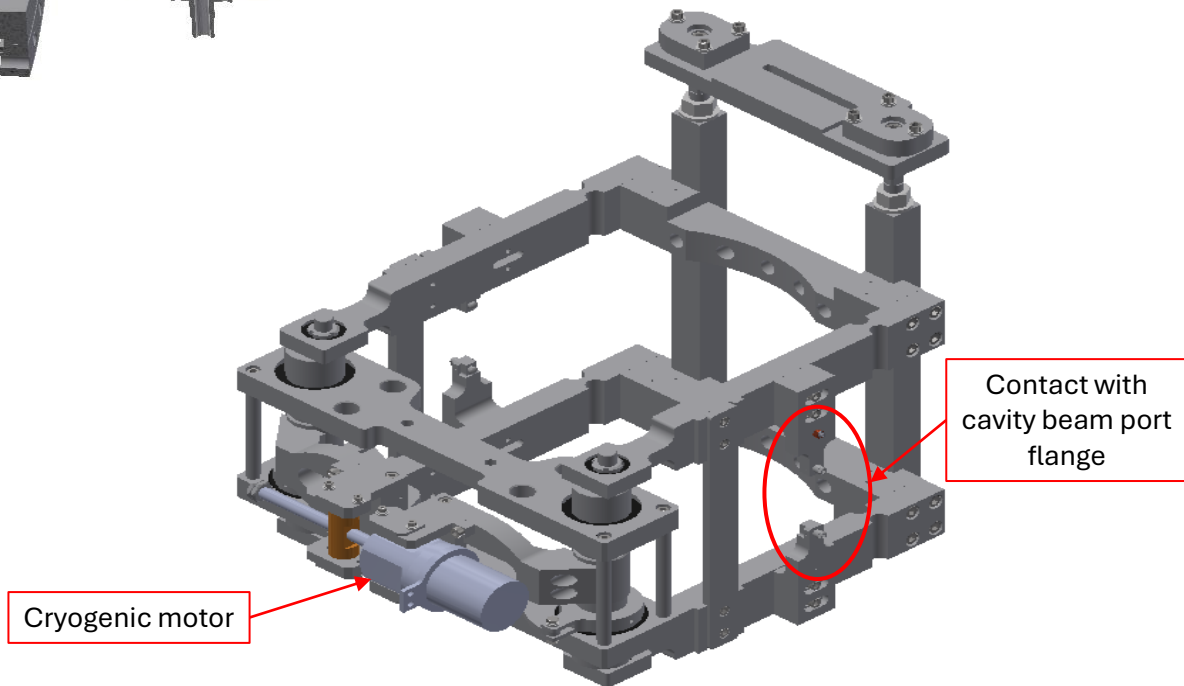
02 고주파 가속관: HWR 가속모듈



02 고주파 가속관: HWR 가속관 외 장치



Power coupler



Tuner

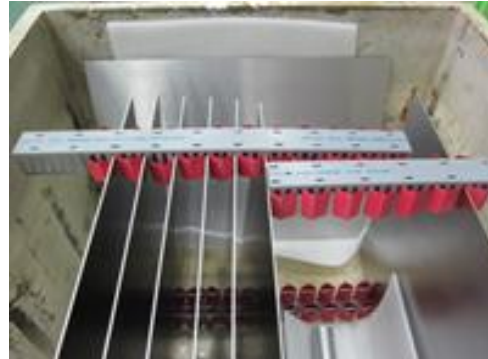
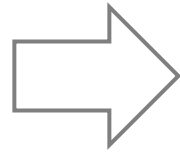
02 고주파 가속관: HWR 제작



■ HWR: 원자재 검수

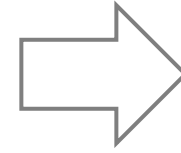


Material



Material inspection

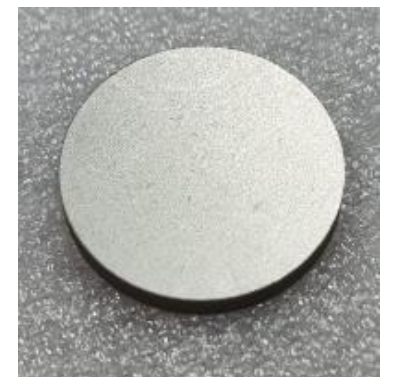
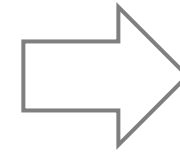
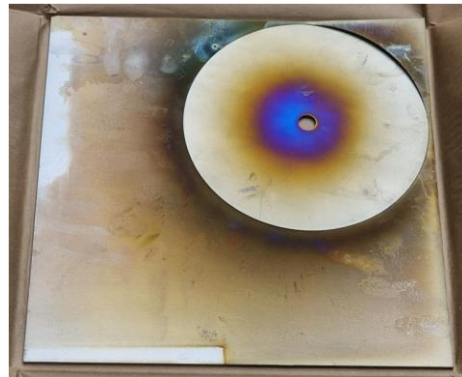
- Visual inspection, Soaking test
- Structural characteristics



Cutting of materials



브라질이 전 세계 생산량의 95% 공급

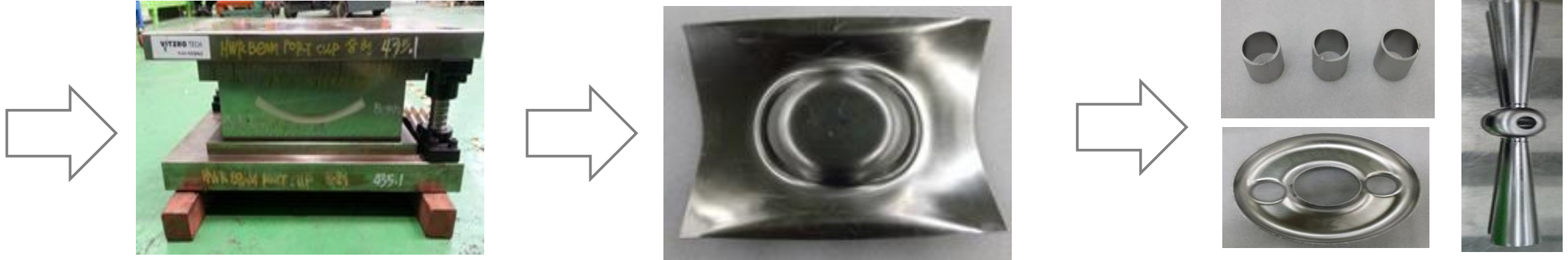


EDM (Electrical Discharge Machining): (좌) 실패 사례, (우) 정상 공정

02 고주파 가속관: HWR 제작

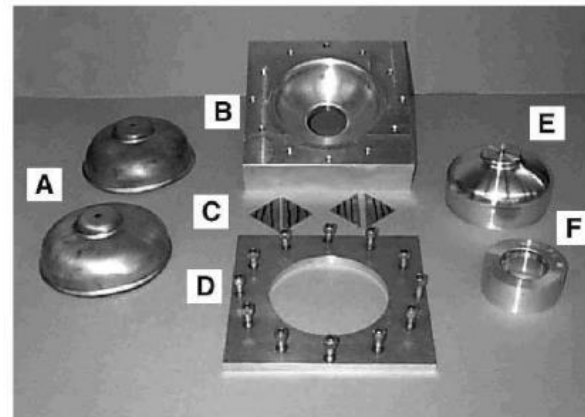
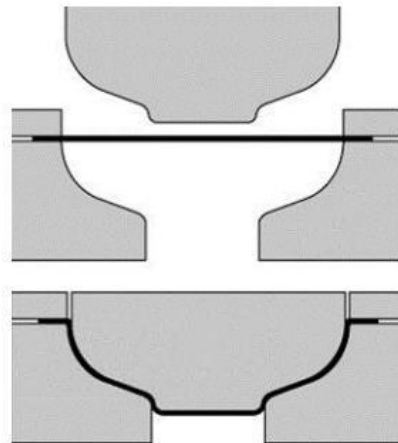


- HWR: Deep drawing



Pressing & machining for parts

Deep Drawing



02 고주파 가속관: HWR 제작



■ HWR: Deep drawing

Large grain



Fine grain



- Difficulty due to deformation caused by asymmetric grains
- Relatively cheap
- Grain size : from several to more than 10 cm



Half-cell made by large-grain disk

- Easy and stable fabrication
- **Grain size : a few to several 10 μm**

	H	C	O	N	Fe	Si	Ta	RRR
Large grain	< 5	< 10	< 10	< 10	< 10	< 10	80	416
Fine grain	< 10	40	< 10	40	20	20	100	258

02 고주파 가속관: HWR 제작



- HWR: Mechanical grinding

Mechanical Grinding



02 고주파 가속관: HWR 제작

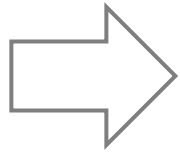


■ HWR: Electron beam welding

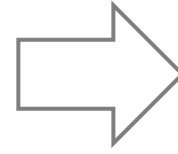


Clamp-up test

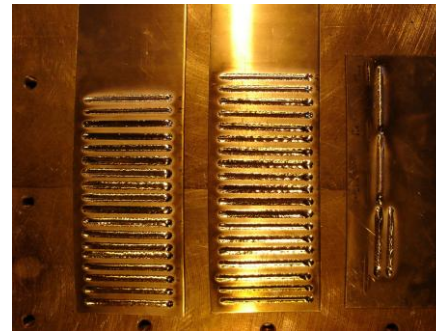
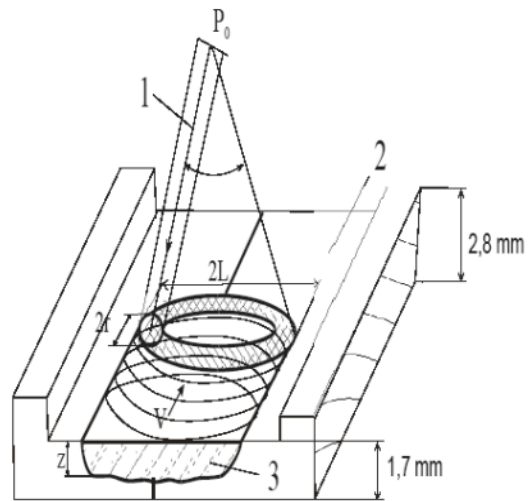
- Frequency adjustment before final welding



E-beam welding



Ultrasonic cleaning (USC)



02 고주파 가속관: HWR 제작



■ HWR: 표면 처리



BCP



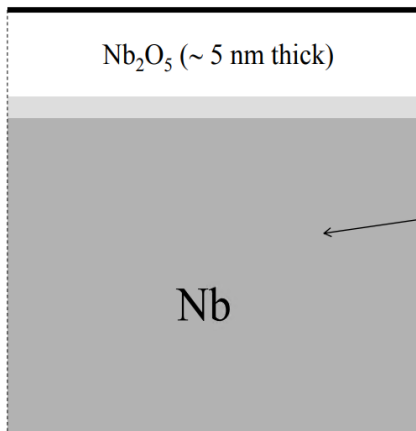
HPR



High temperature heat treatment

Nb Surface

Buffered Chemical Polish (BCP)



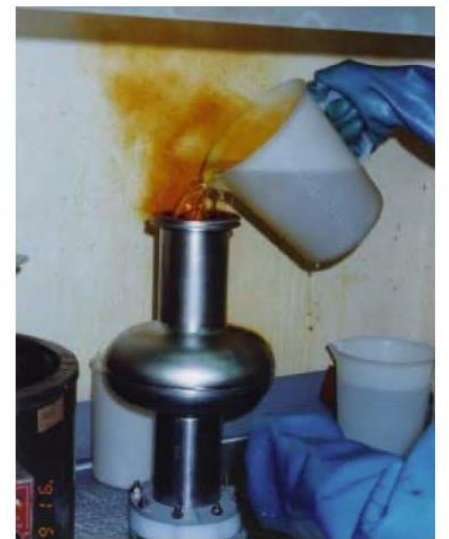
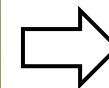
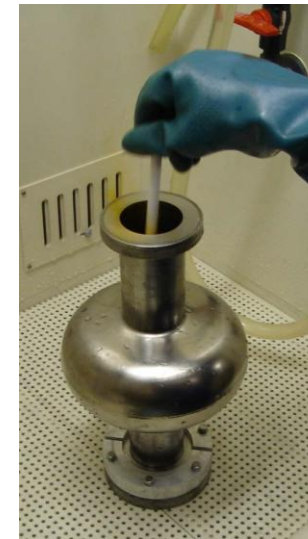
HF (49%), HNO₃ (65%), H₃PO₄ (85%)
Mixture 1:1:1, or 1:1:2 by volume typical

불산, 질산, 인산

Oxidation
 $2\text{Nb} + 5\text{HNO}_3 \rightarrow \text{Nb}_2\text{O}_5 + 5\text{NO}_2$ → Brown gas

Reduction
 $\text{Nb}_2\text{O}_5 + 6\text{HF} \rightarrow \text{H}_2\text{NbOF}_5 + \text{NbO}_2\text{F} + 0.5\text{H}_2\text{O} + 1.5\text{H}_2\text{O}$

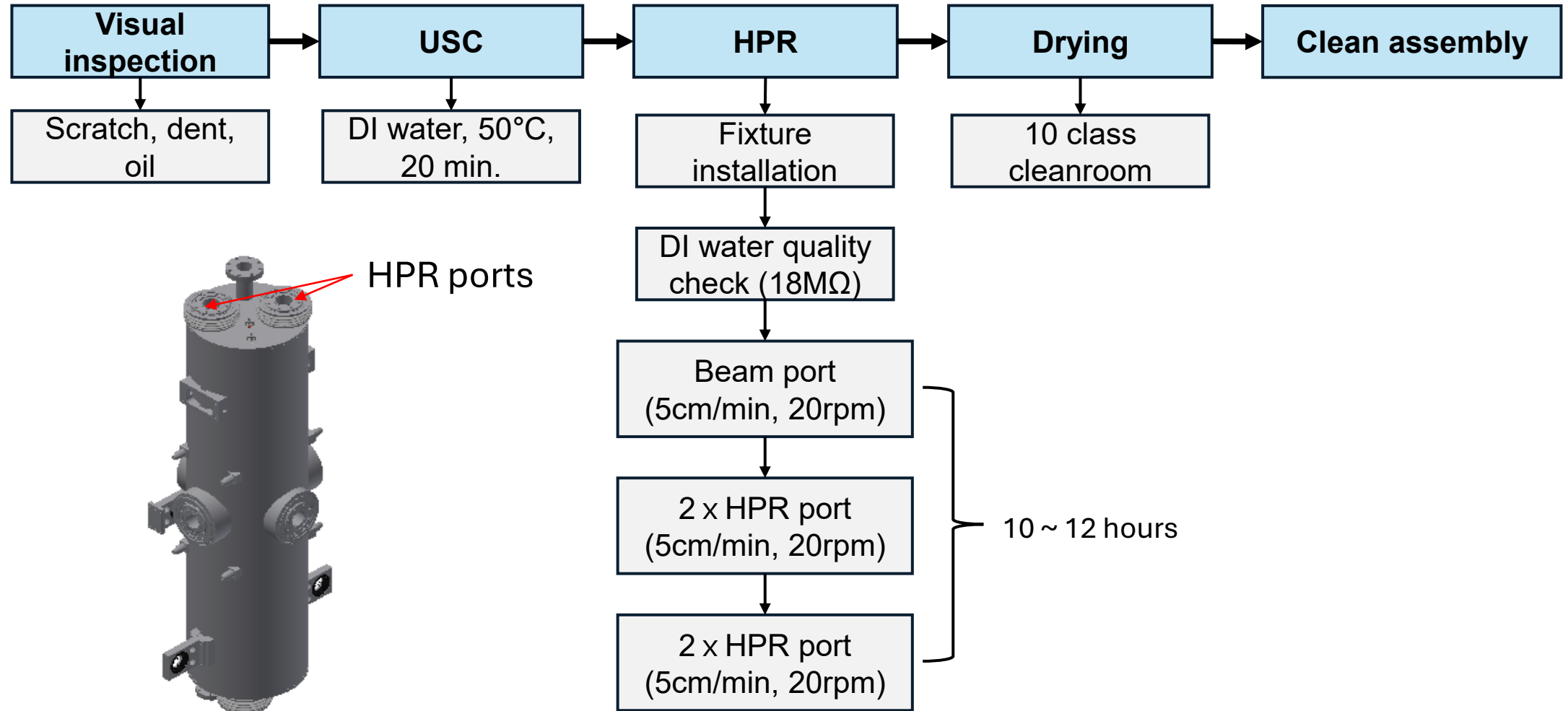
$\text{NbO}_2\text{F} + 0.5\text{H}_2\text{O} + 4\text{HF} \rightarrow \text{H}_2\text{NbOF}_5 + 1.5\text{H}_2\text{O}$



02 고주파 가속관: HWR 제작



■ HWR: 표면 처리, HPR 상세



02 고주파 가속관: HWR 제작



- HWR: 표면 처리, USC

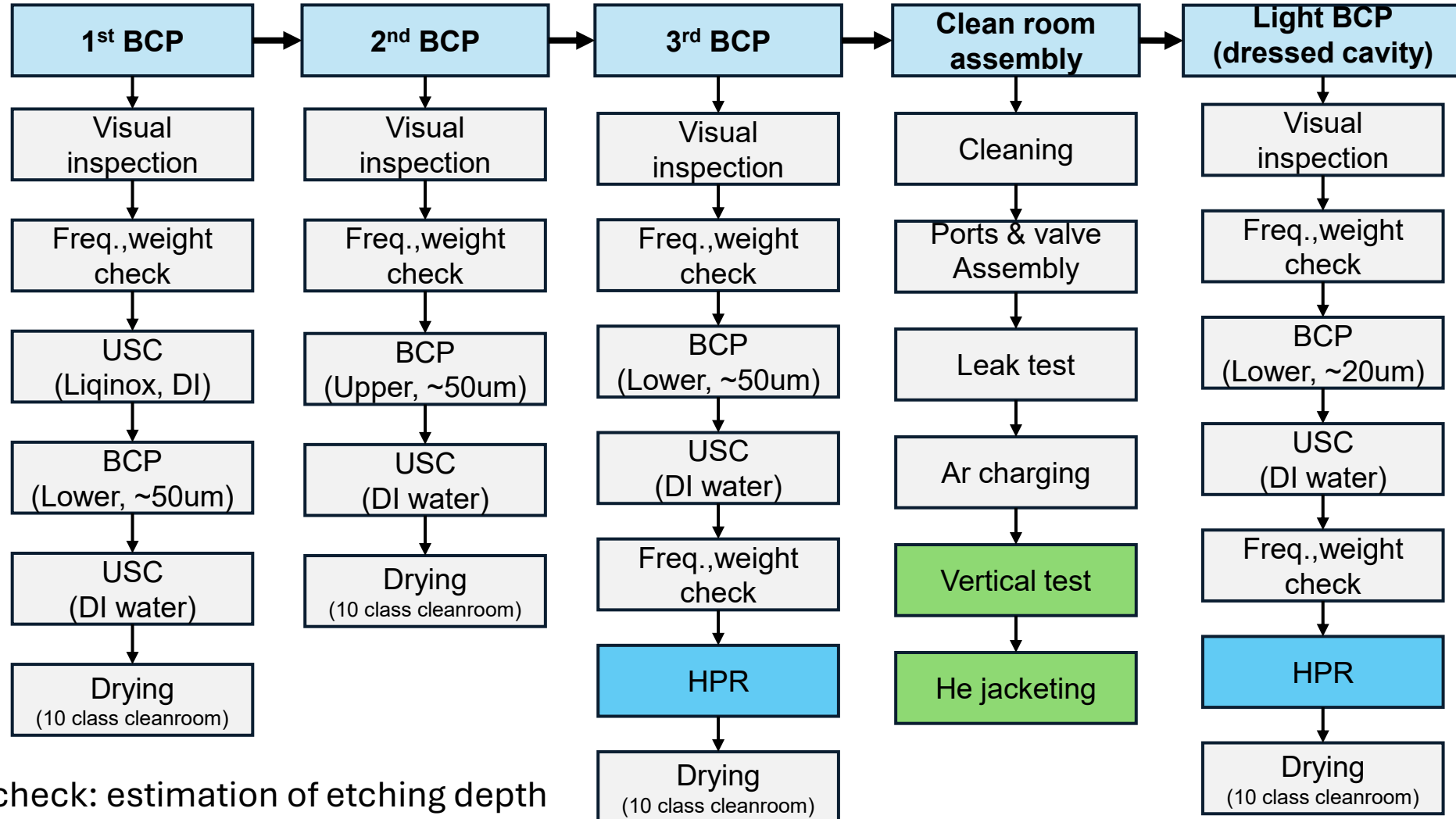


- Class1000 (ISO6) cleanroom
- Double bath type
 - 1st bath(degreasing) : 1% liquinox
 - 2nd bath(rinsing) : DI water
- Ultrasonic Power : 1.5kW
- Ultrasonic Frequency : 40kHz
- Heating up to 60°C

02 고주파 가속관



■ HWR: BCP procedure in detail



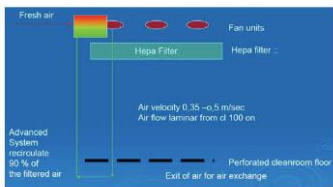
* Weight check: estimation of etching depth

02 고주파 가속관

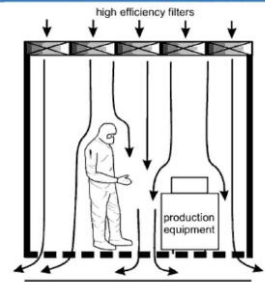
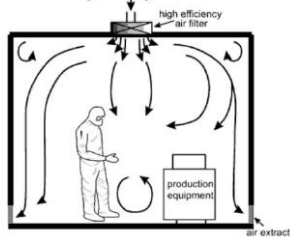


■ HWR: Clean Assembly

Cleanroom Classification



Non-Unidirectional airflow type (JLab)



Unidirectional airflow type (DESY)

ISO Classification number

Maximum concentration limits (particles/m³ of air) for particles equal to and larger than the considered sizes shown below

	$\geq 0.1\mu\text{m}$	$\geq 0.2\mu\text{m}$	$\geq 0.3\mu\text{m}$	$\geq 0.5\mu\text{m}$	$\geq 1\mu\text{m}$	$\geq 5.0\mu\text{m}$
ISO Class 1	10	2				
ISO Class 2	100	24	10	4		
ISO Class 3	1 000	237	102	35	8	
ISO Class 4	10 000	2 370	1 020	352	83	
ISO Class 5	100 000	23 700	10 200	3 520	832	29
ISO Class 6	1 000 000	237 000	102 000	35 200	8 320	293
ISO Class 7				352 000	83 200	2 930
ISO Class 8				3 520 000	832 000	29 300
ISO Class 9				35 200 000	8 320 000	293 000

ISO 14644-1 Classes
FS 209 Classes

Class 3
Class 1

Class 4
Class 10

Class 5
Class 100

Class 6
Class 1000

Class 7
Class 10, 000

Class 8
Class 100, 000

↑
Cavity
assembly

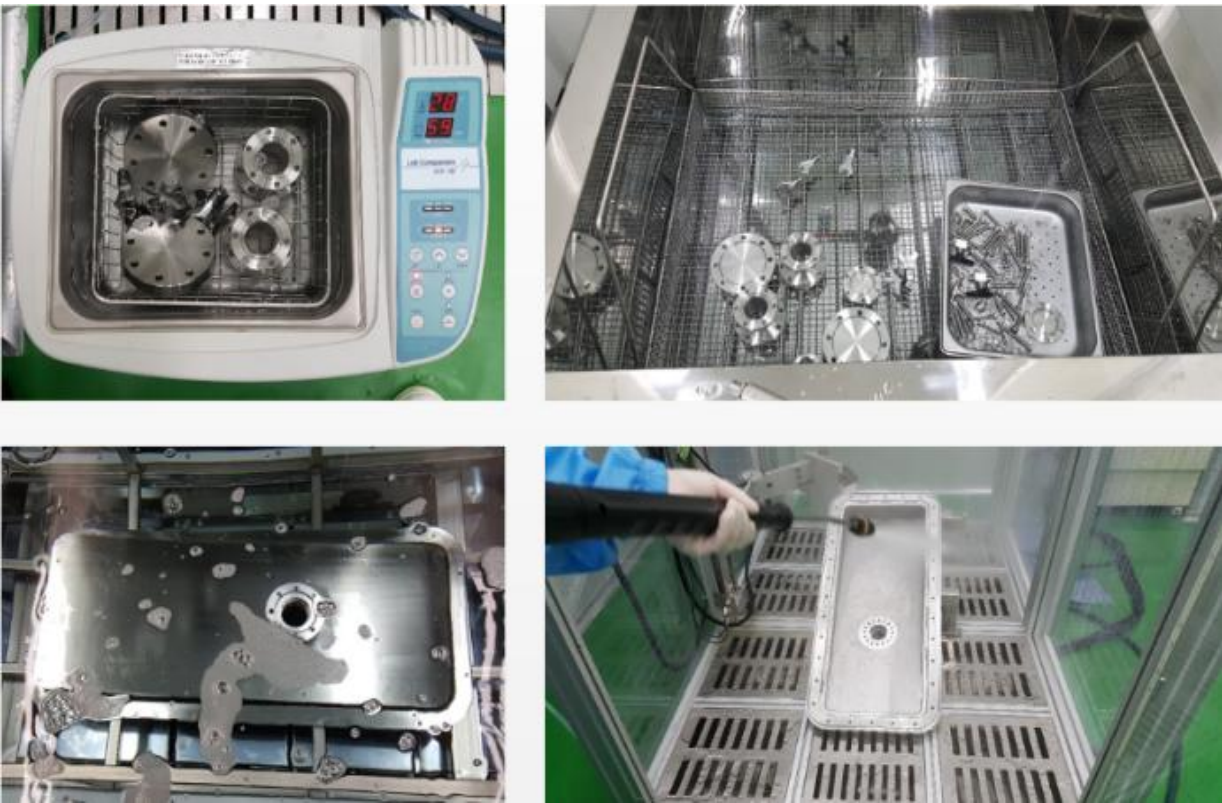
↑
Cleanroom
for SRF

↖
반도체

02 고주파 가속관



- HWR: Clean Assembly



USC & HPR

Parts using USC	Parts not using USC
Less than 1 particle ($\leq 0.3\mu\text{m}$) /5s	Less than 1 particle ($\geq 1.0\mu\text{m}$) /1s

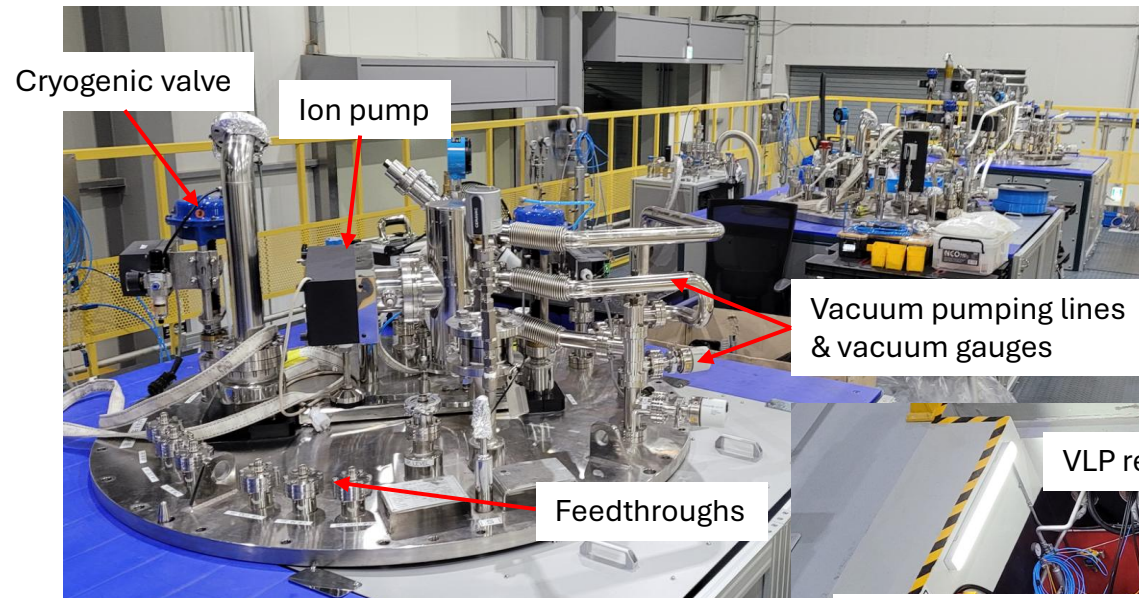
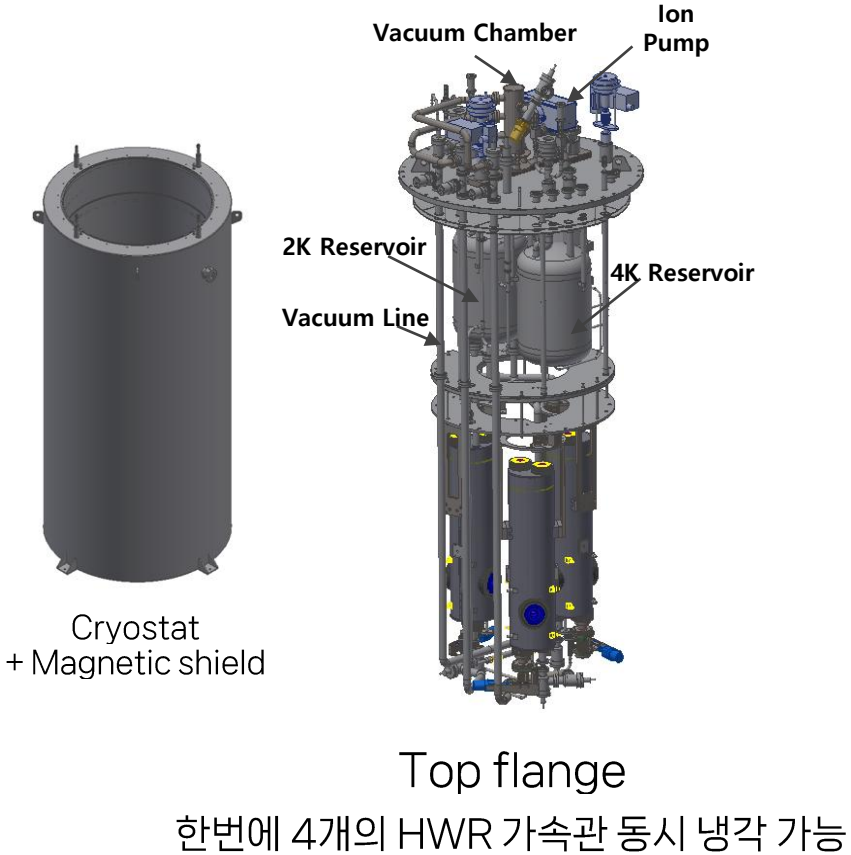


Particle counting

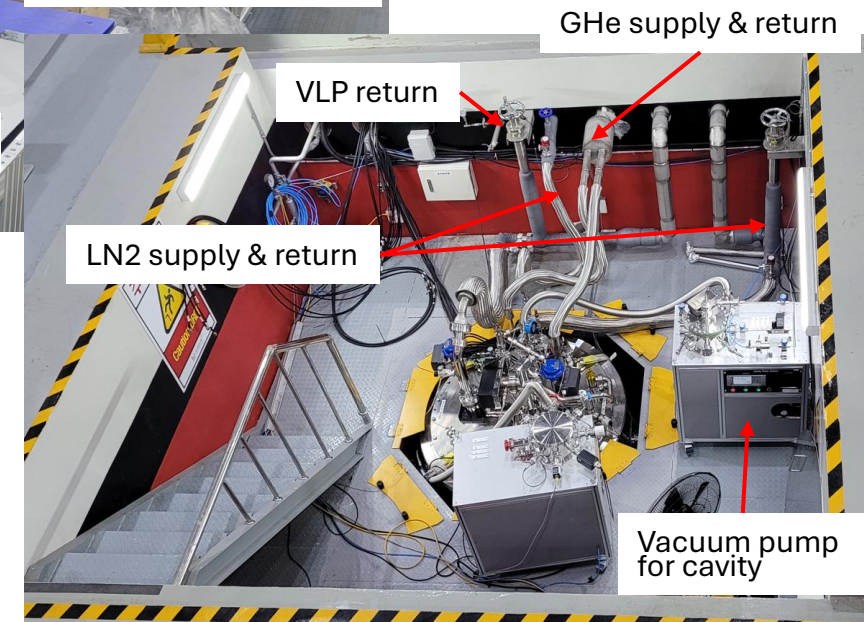
02 고주파 가속관



■ HWR: Vertical test facility



Assembly area(clean room) for vertical test

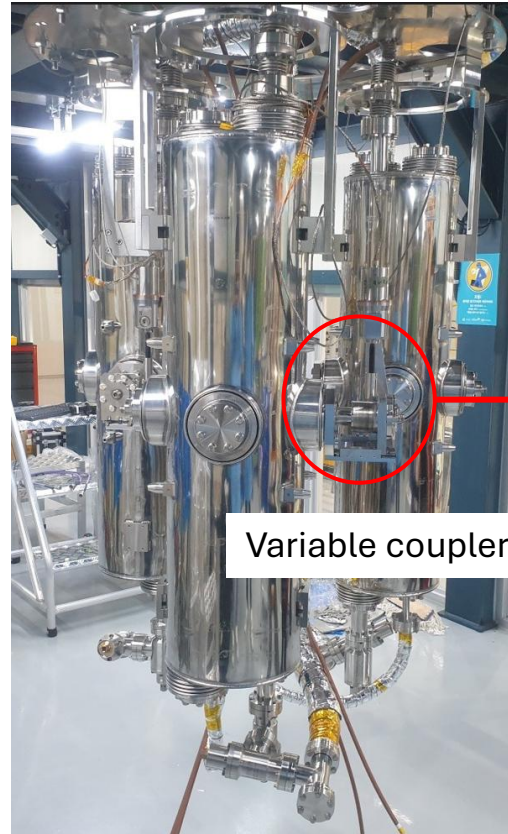


Top flange in the vertical test pit

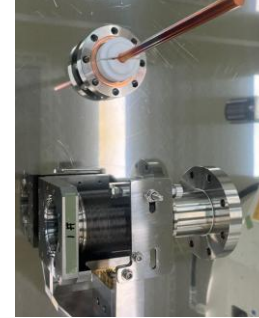
02 고주파 가속관



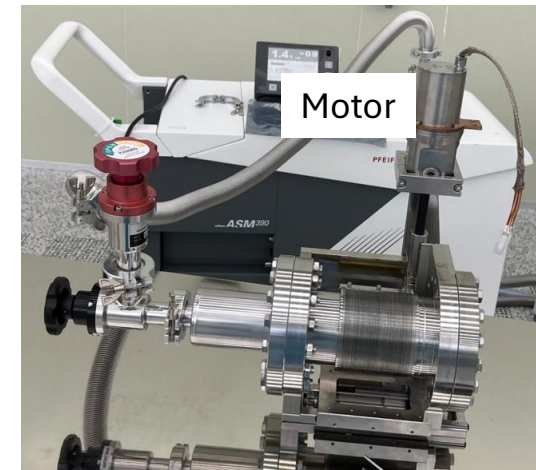
- HWR: Vertical test facility



Inner conductor



Outer conductor and bellows

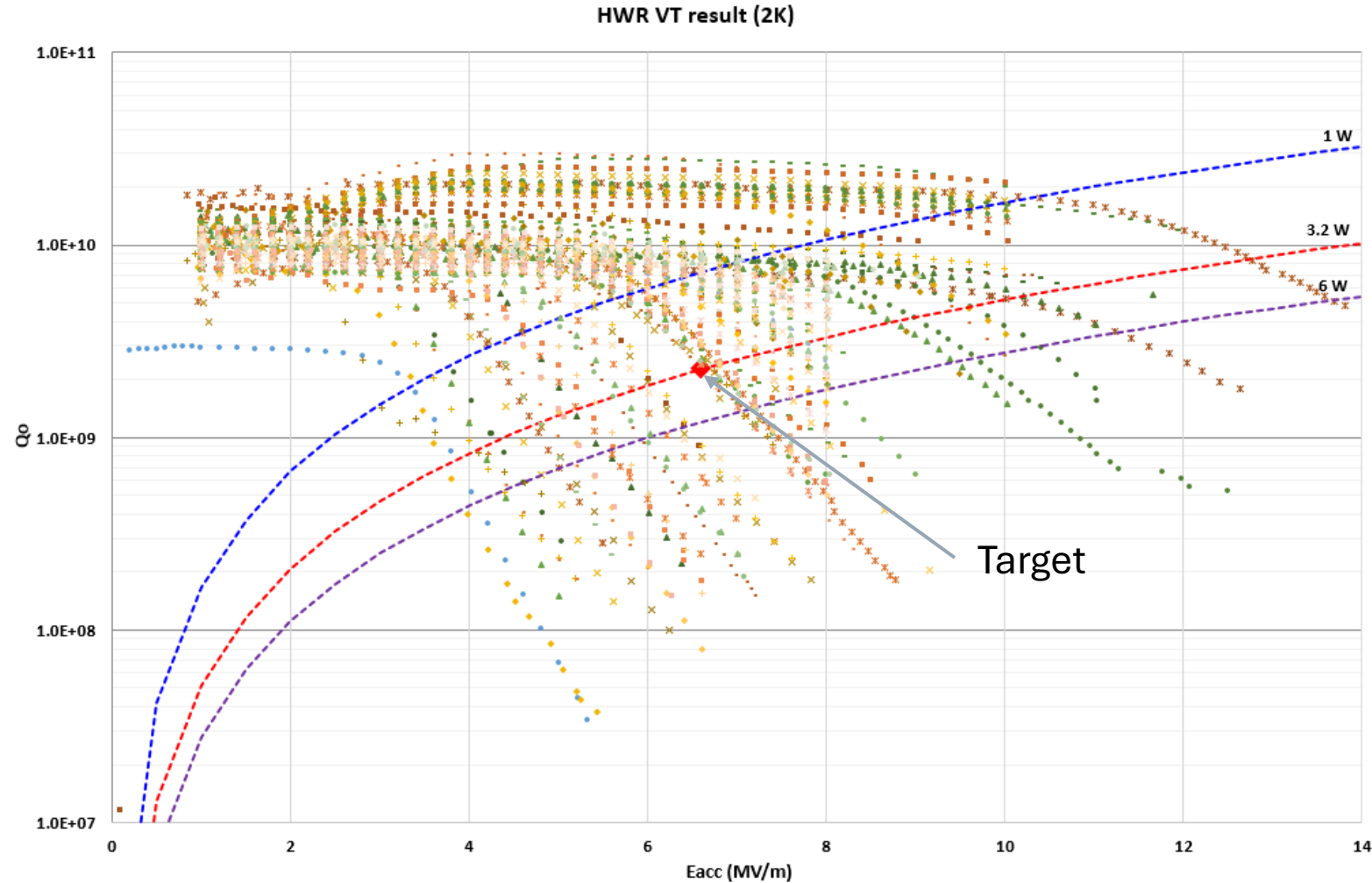


Motor

02 고주파 가속관



■ HWR: VT Results

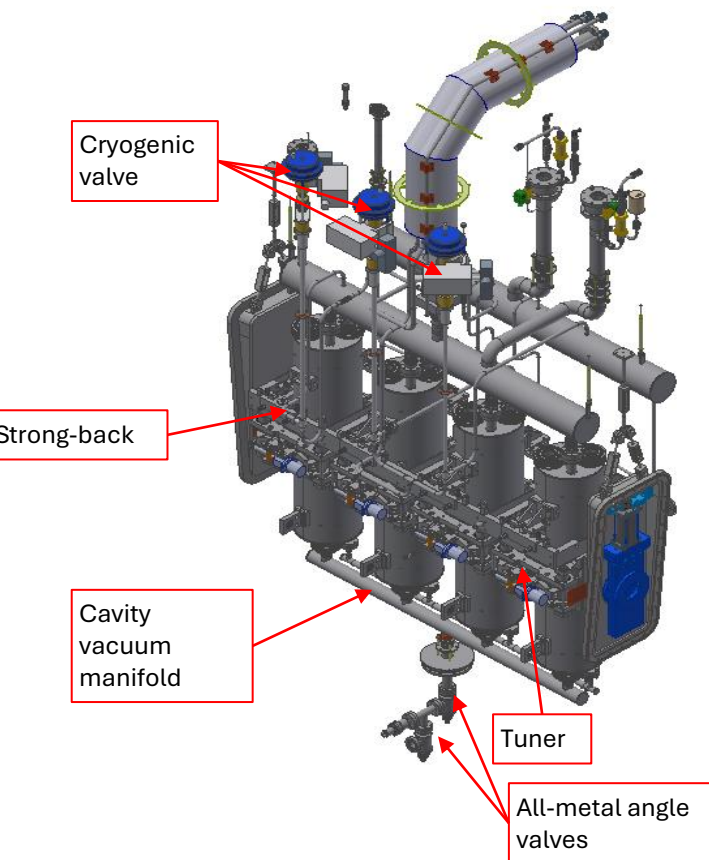


E_{acc} : 6.6 MV/m, $Q_0=2.3e+9@2.05K$, Number of cavity: 106 ea

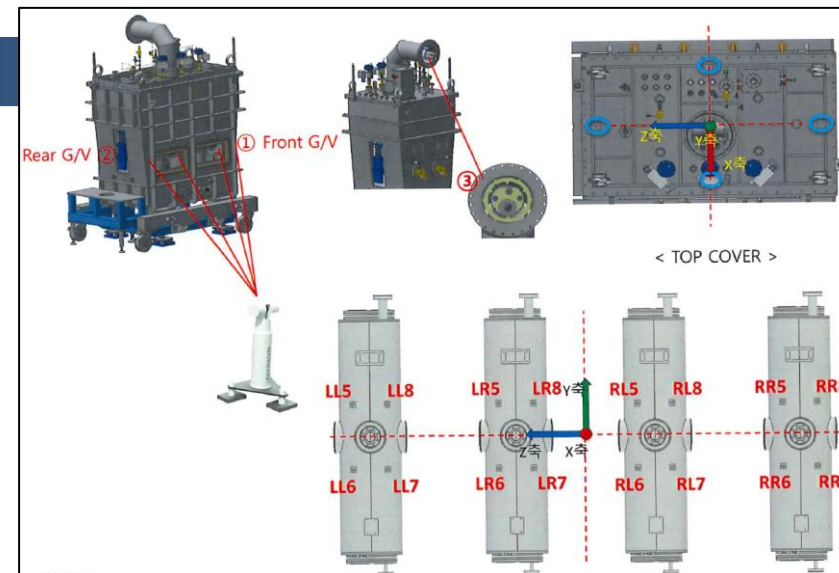
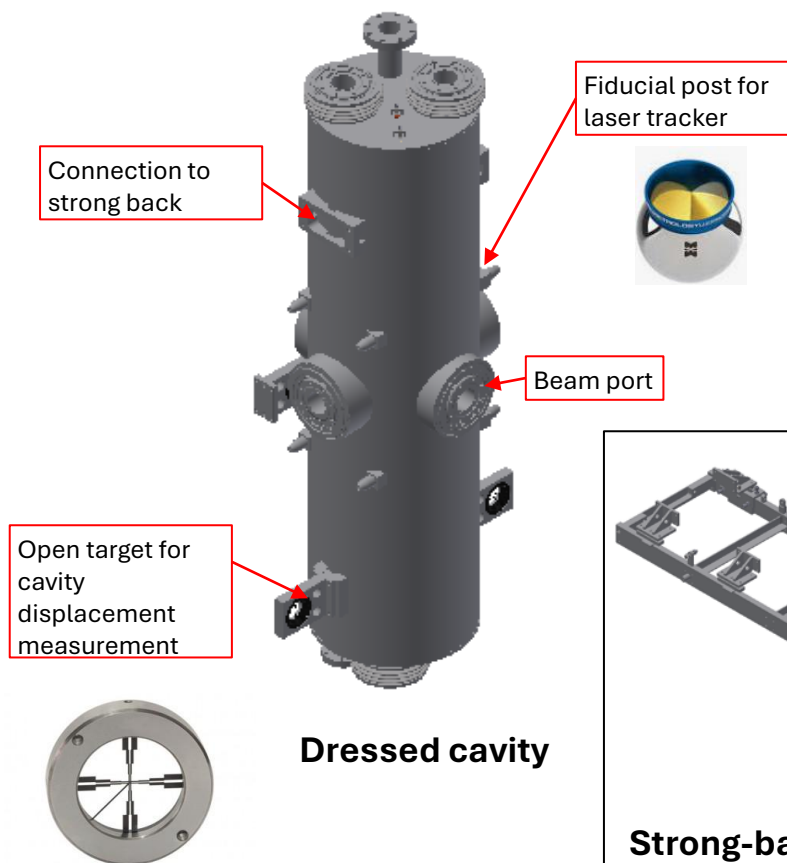
02 고주파 가속관



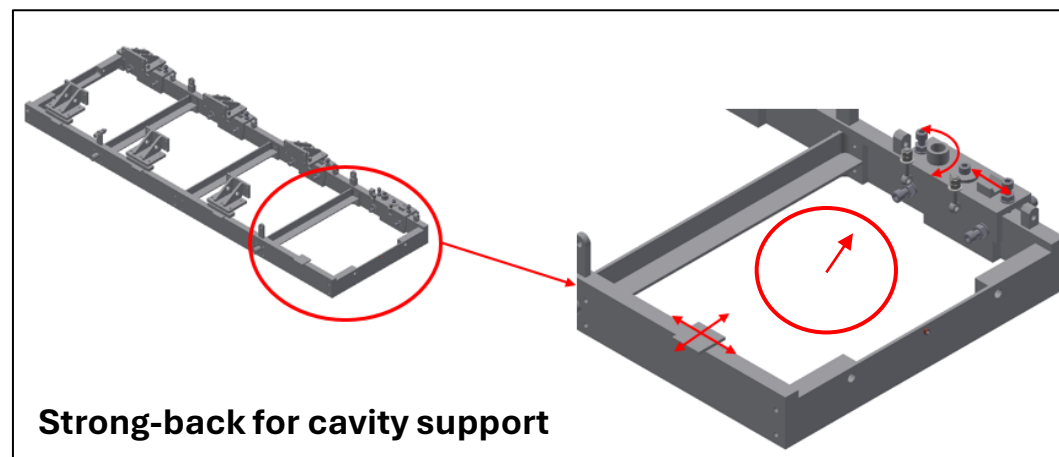
■ HWR: 가속모듈 조립



Precision assembly in cryomodule



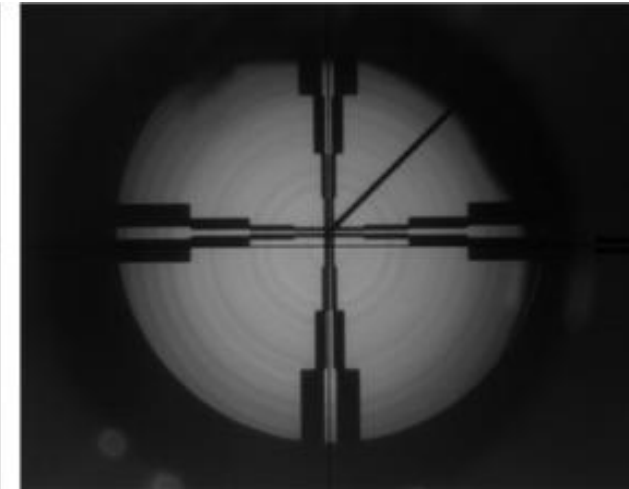
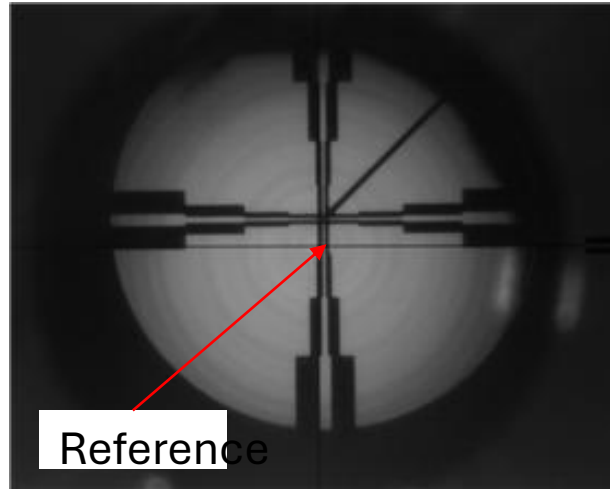
Cavity position measurement during assembly



02 고주파 가속관



■ HWR: 가속모듈 조립



Measurement of open target position before and after cool-down

Micro Alignment Telescope (MAT)

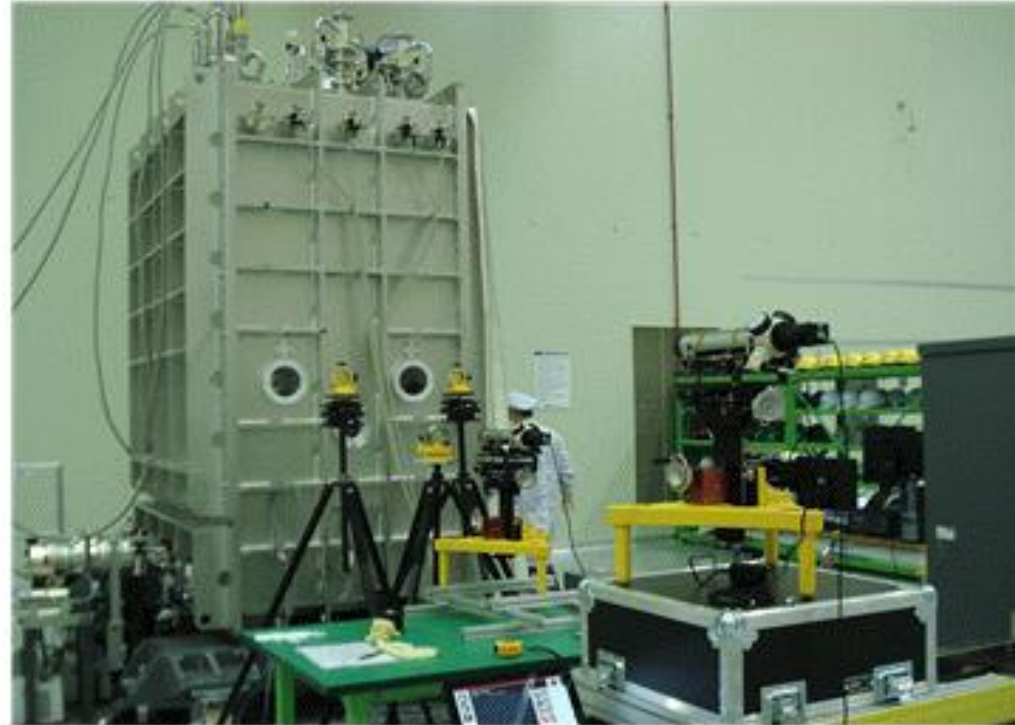
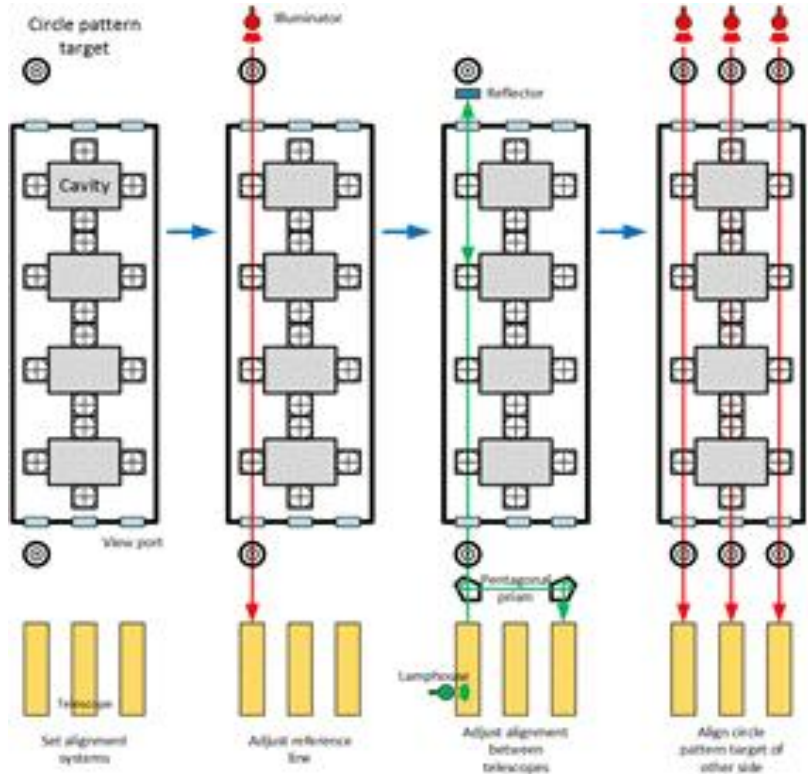
- Measurement of cavity's displacement before and after vacuum pumping and cool-down
- Location of the beam port can be estimated by the displacement of the open targets



02 고주파 가속관



■ HWR: 가속모듈 조립



- Open targets on the beam ports to know the actual position of beam ports
- To check the repeatability and to know the amount of vertical calibration

02 고주파 가속관



- HWR: Horizontal test facility



Horizontal test bunkers

Helium distribution lines

신재희 연구위원, "IRIS Cryogenics"

Valve box for HT



RF transmission line

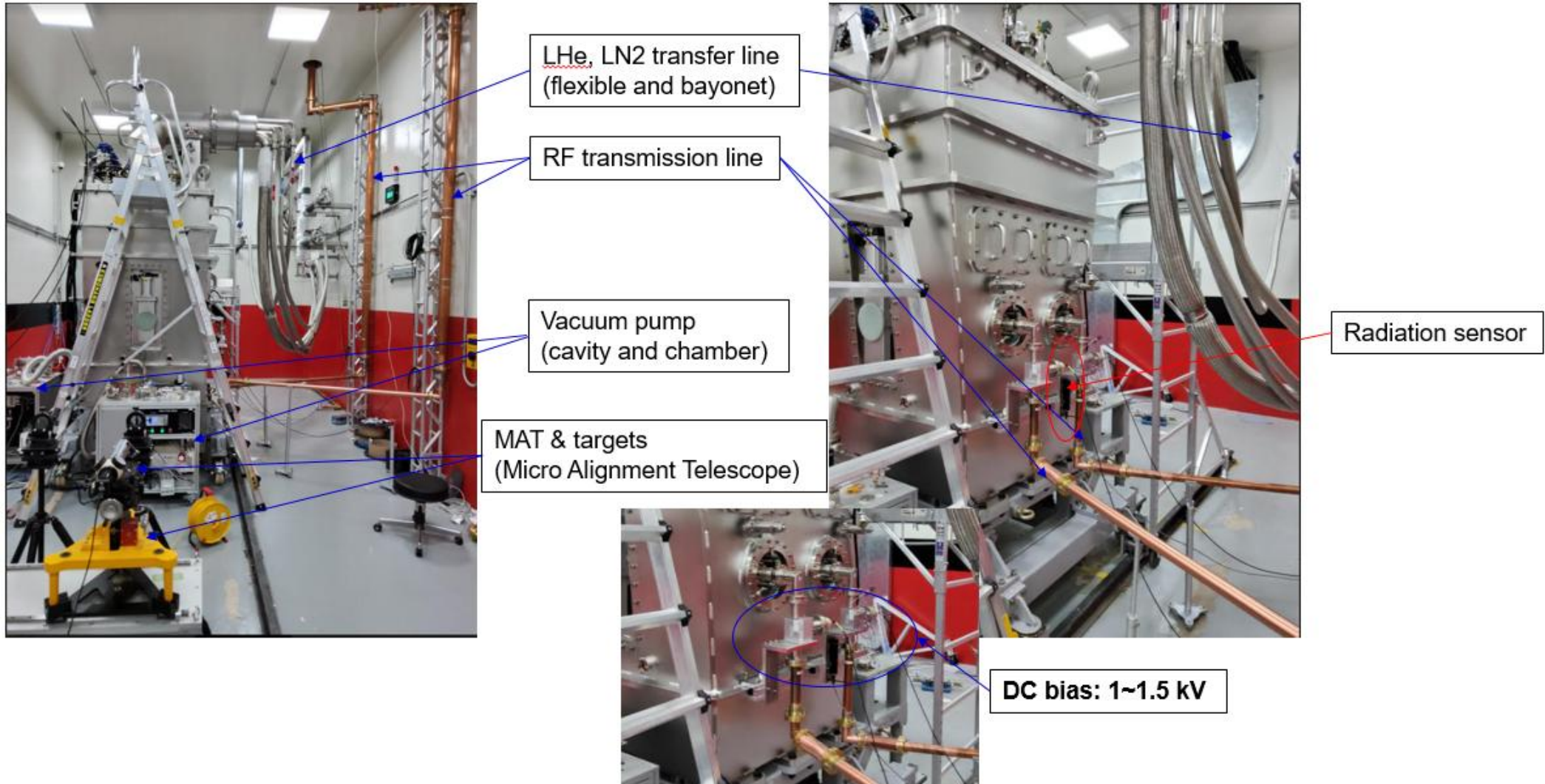
설경태 연구위원, "IRIS RF other than SRF Cavities"

SSPA

02 고주파 가속관



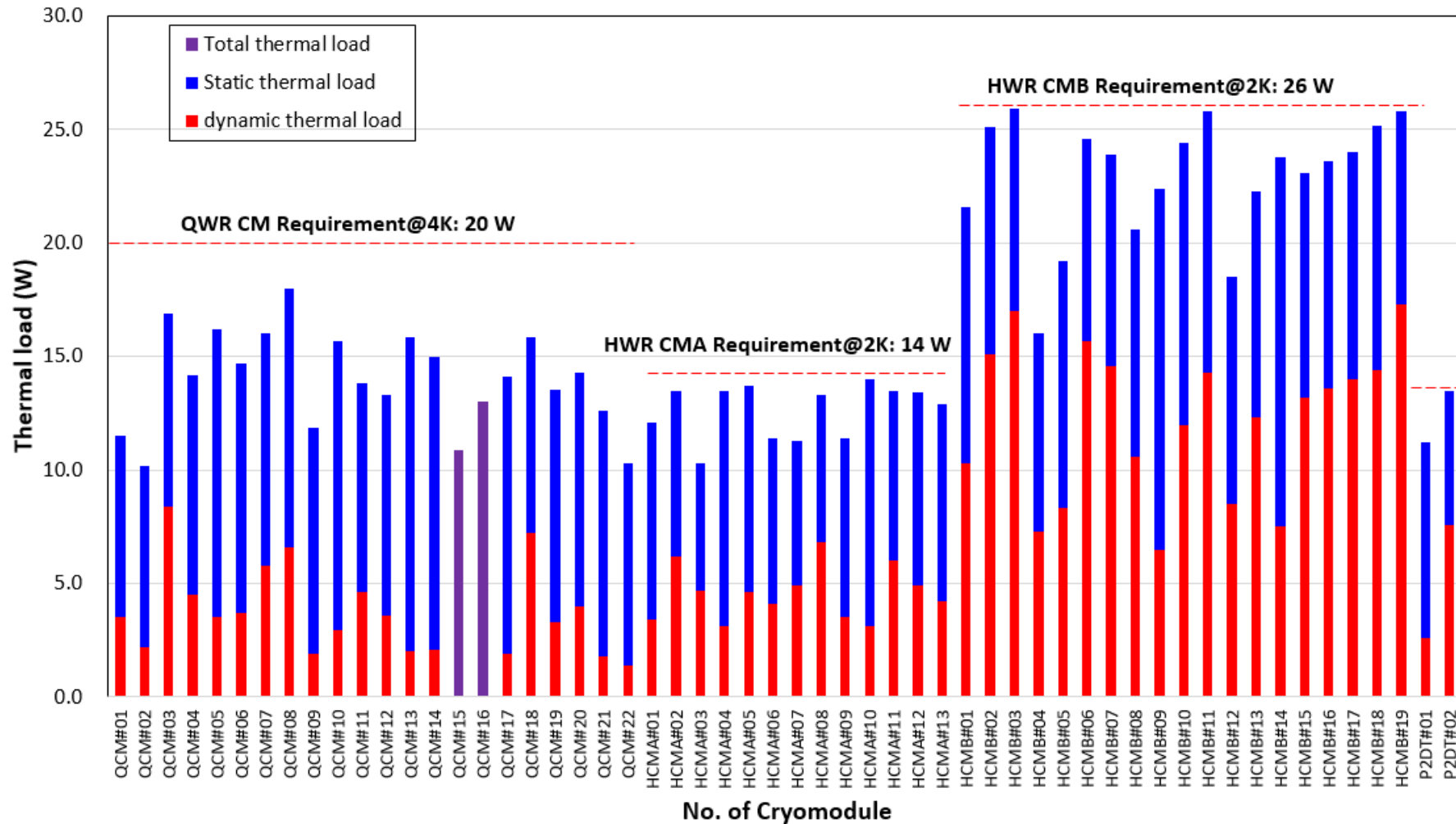
- HWR: Horizontal test facility



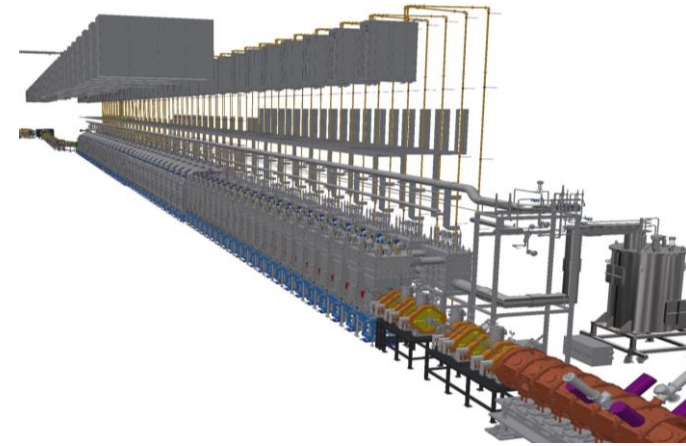
02 고주파 가속관



■ HWR: Thermal load measurement results



- Dynamic thermal load of each cryomodule is the sum of the dynamic thermal load of cavities in the cryomodules



SCL3 Installation



- 목 차 -

01 개요

- RF(Radio Frequency)란?

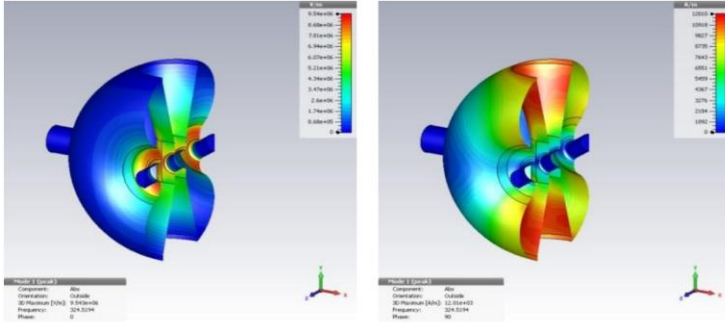
02 고주파 가속관

- 기초
- RAON 가속기 시스템 개요
- HWR 가속관 제작 및 활용 사례
- SSR1 가속관 연구 현황

02 고주파 가속관: SSR1, 설계

Electromagnetic field analysis

E-field & B-field distributions



Minimize $E_{pk}/E_{acc} \rightarrow$ Suppress field emission

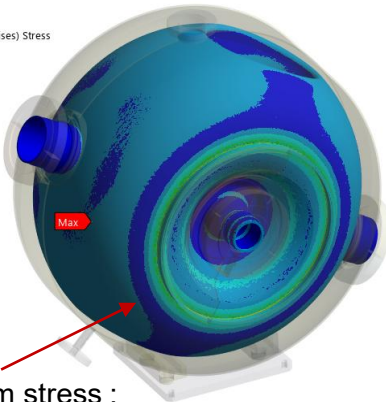
Minimize $B_{pk}/E_{acc} \rightarrow$ Enable higher operational gradient

Structure analysis

Under vacuum after jacket-stiffening ring welding

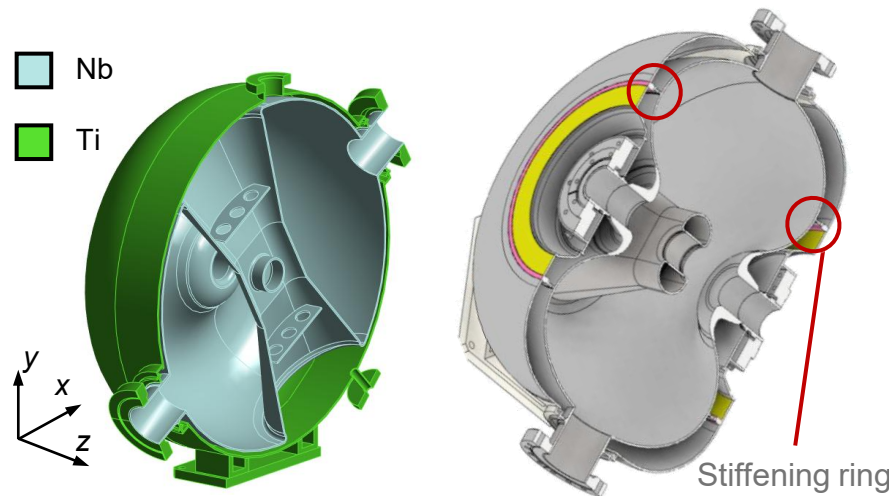
K: Pressure
Stress of Nb Parts
Type: Equivalent (von-Mises) Stress
Unit: MPa
Time: 1 s

39.446 Max
35.065
30.684
26.302
21.921
17.539
13.158
8.7765
4.3951
0.013703 Min



Maximum stress :
39.5 MPa < (47.0 MPa)

Nb
Ti

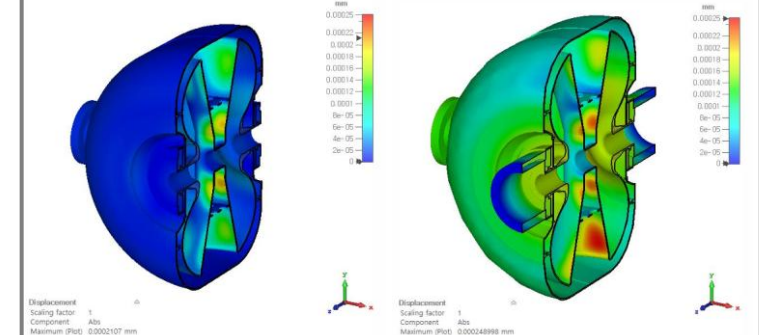


Stiffening ring

Lorentz force detuning (LFD)

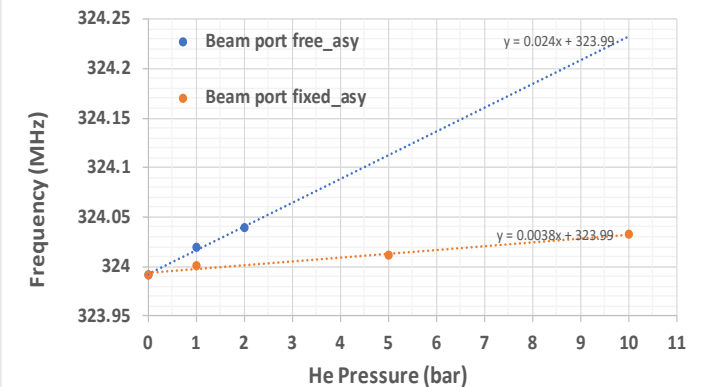
Beam port fixed

Tuner assembled condition



- For beam port fixed, LFD = -2.45 Hz / (MV/m)²
- For tuner assembled, LFD = -3.67 Hz / (MV/m)²

df/dp analysis



Beam port free condition : 24 kHz/mbar

Beam port fixed condition : 3.8 kHz/mbar

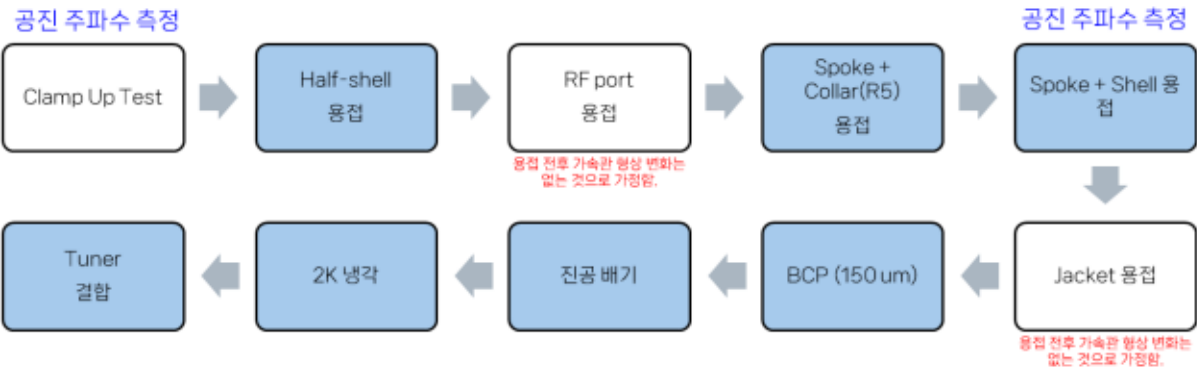
02 고주파 가속관: SSR1, 설계



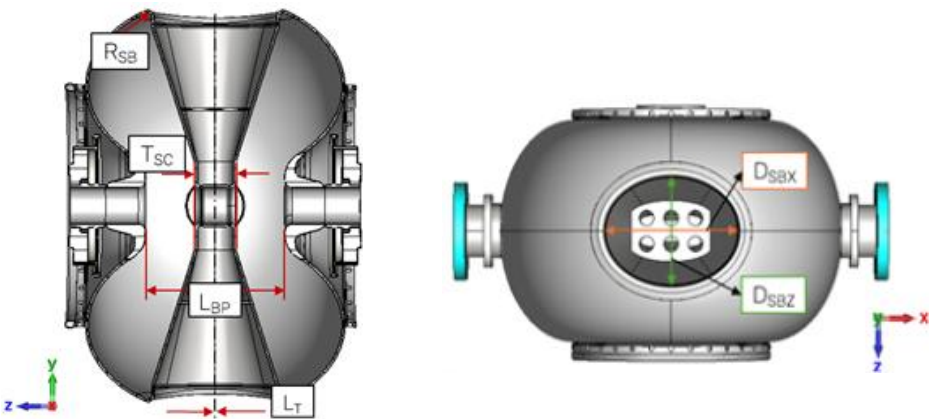
SSR1 가속관 가공 중 예상되는 주파수 변화 민감도 해석

연구내용 ■ 해석을 통하여 가속관 형상 변수에 따른 주파수 변화 민감도 확인

✓ 클램프업 시험 후 가속관 주파수에 영향을 미치는 공정 식별

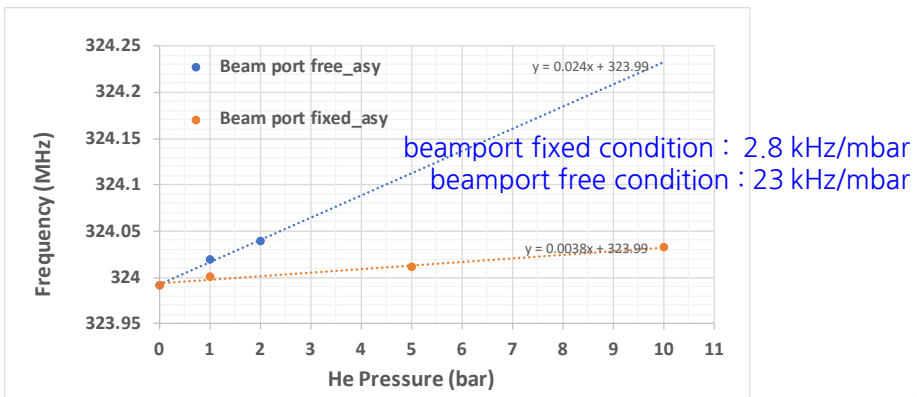


✓ 해석을 통한 주파수 변화 및 민감도



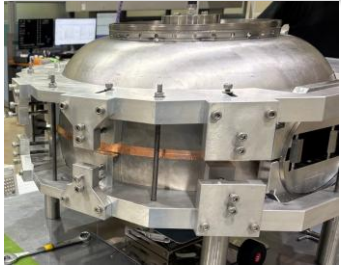
변수	주파수 변화 및 민감도	비고
R_{SB}	+196 kHz	Spoke base의 Collar 부품 곡률
L_{BP}	+235 kHz/mm	Beam port 간 간격
L_T	+129 kHz/mm	Half-shell의 trimming 길이
T_{SC}	-462 kHz/mm	Spoke Center 두께
D_{SBX}	+235 kHz/mm	Spoke base의 직경 (x축)
D_{SBZ}	+287 kHz/mm	Spoke base의 직경 (z축)

✓ (df/dp 해석) 헬륨 압력과 주파수 해석 : 선형성 확인



02 고주파 가속관: SSR1, 제작

Clamp up test



- Sub-part alignment for frequency tuning and optimal positioning
- Frequency adjustment using shell trimming (conventional) and beam cup trimming (recently) methods

Single spoke resonator1 (SSR1)

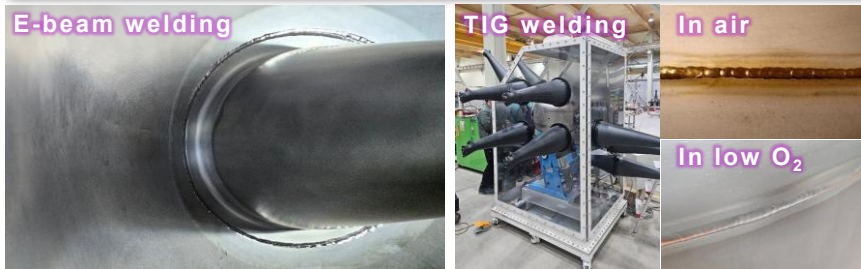


Buffered chemical polishing (BCP)



- Wet chemical etching process for Nb to remove surface damages, contaminations, and native oxides
- $\text{HF} : \text{HNO}_3 : \text{H}_3\text{PO}_4 = 1 : 1 : 2$
(HF : 40%, HNO_3 : 65%, H_3PO_4 : 85%)
- $\sim 150\mu\text{m}$

E-beam & Tungsten inert gas welding

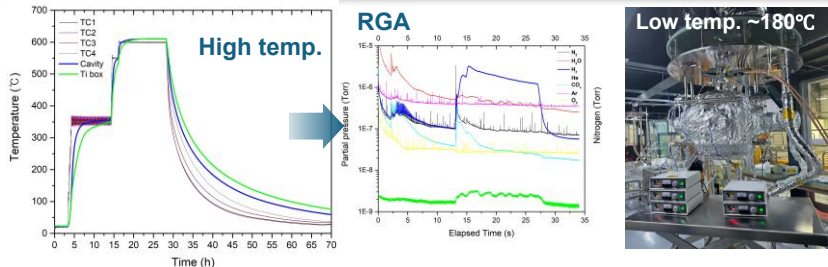


High pressure rinsing (HPR)



- Cleaning process to remove residual particles, acids, and contaminants from Nb surfaces.
- The critical step in SRF cavity preparation; it strongly influences field emission (FE), resulting in quality factor (Q_0)

High/low temperature baking



- For hydrogen degassing from Nb
- For reduction of SEY

Clean assembly

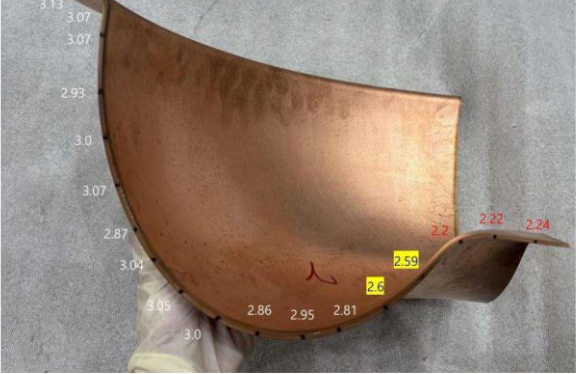


- Assembly of SRF cavity components in a cleanroom to prevent particle contamination and ensure ultra-high vacuum (UHV) conditions
- Critical process similar to the HPR for minimizing FE and achieving Q_0

02 고주파 가속관: SSR1, 제작



Press sample test



shell visual inspection



polishing dents



beamport cup



spoke

2025년 7월 03일

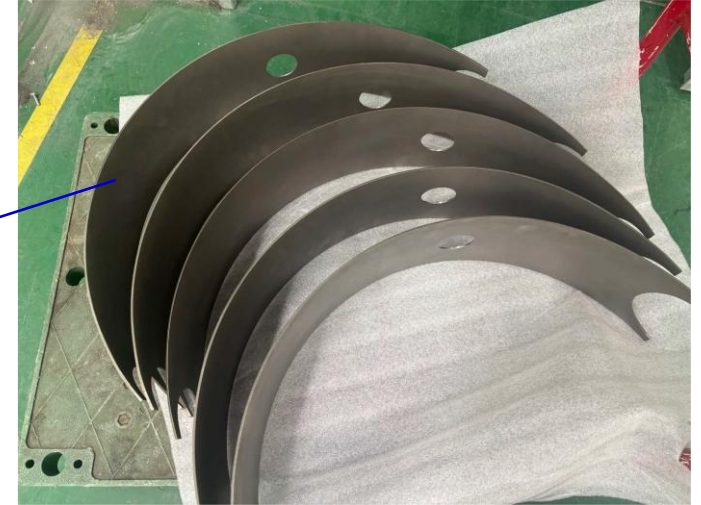
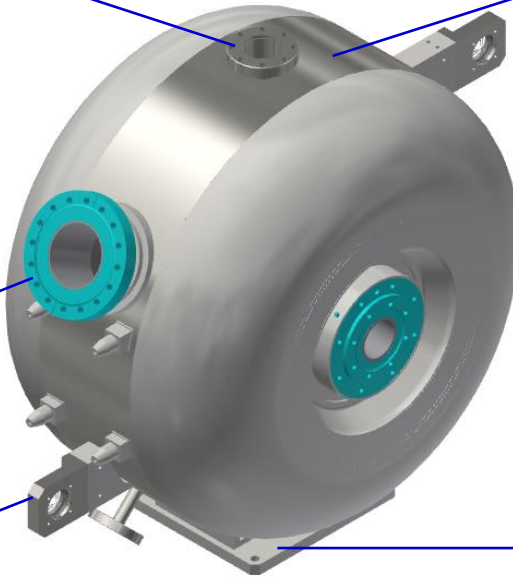
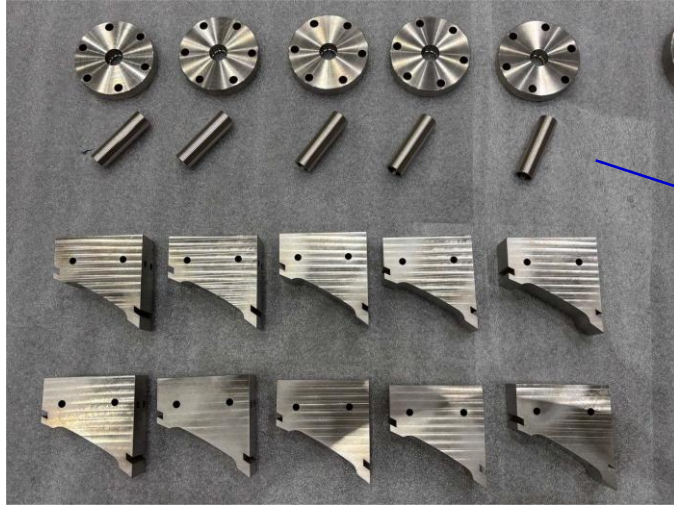
- Half shell is fabricated by deep drawing process from raw material
- Flaws on cavity inner surface due to deep drawing process were eliminated
- Beam port cup and stiffener ring are welded to half shell by E-beam welding
- Stitch welding to minimize the cavity deformation (stiffening ring)
 - 30 % of each outer / inner diameter of stiffening ring is welded
- Spoke and collar is welded to cavity after clamp up test



stiffening ring

26mm

02 고주파 가속관: SSR1, 제작



02 고주파 가속관: SSR1, 제작

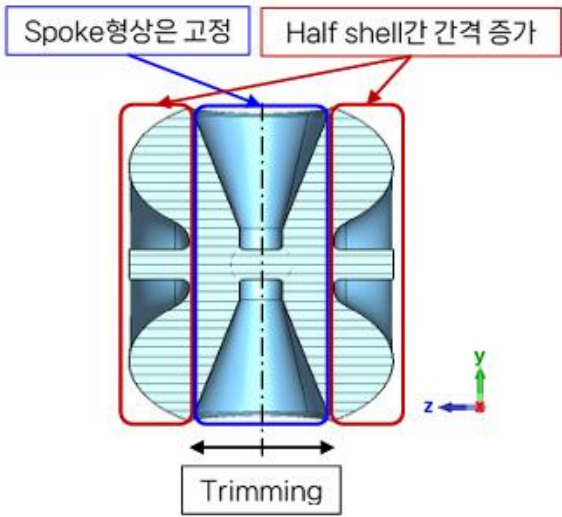


가속관 주파수 튜닝공정 개선

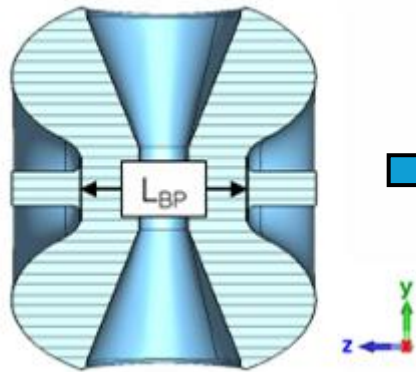
개선결과 주파수 튜닝공정을 위한 트리밍 가공이 최종 용접 품질에 영향을 최소화 하도록 공정 수정 ➡ **최종용접 품질 향상**

- ✓ **(기존 시작품)** 클램프 업 공정을 shell to shell 거리를 조절하여 주파수 조절
이 과정에서 spoke와 shell에 단차 발생하여 최종용접 품질 저하
- ✓ **(시제품 개선)** spoke와 shell간 단차 없도록 용접품질 향상을 위해 빔포트 컵을
연마하여 주파수 튜닝 공정 진행

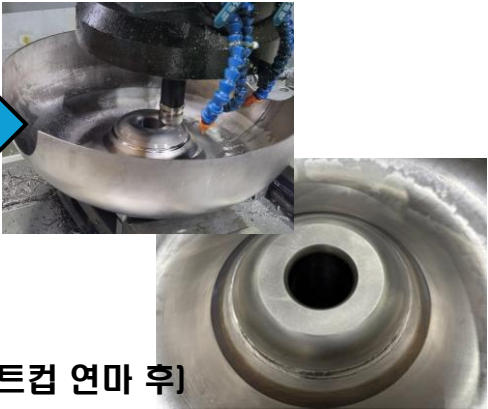
[기존]



[개선]

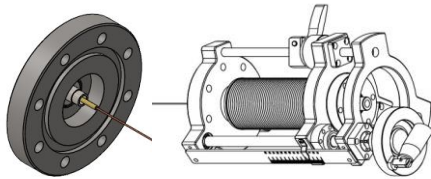


번호	공정	공진 주파수 [MHz]	주파수 변화 [MHz]
8	Tuner 결합	325.000	-0.050
7	2K 냉각 및 운용	325.050	+0.835
6	진공 배기	324.215	+0.095
5	BCP (150 um)	324.120	-0.002
4	Spoke + Shell 용접	324.122	+0.157
3	Spoke + Collar(R5) 용접	323.965	+0.196
2	Half-shell 용접	323.769	-0.039
1	Clamp up Test	323.808	-



[빔포트컵 연마 후]

- ✓ 클램프업 시험용
Variable 픽업커플러 제작



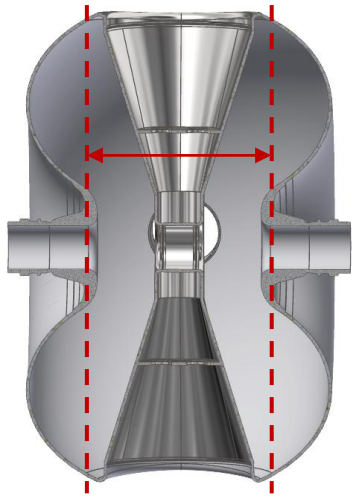
[기존]

[개선]

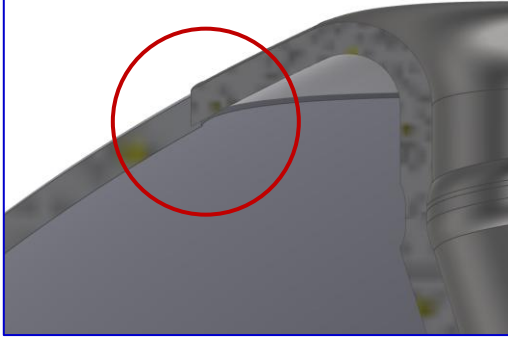
02 고주파 가속관: SSR1, 제작



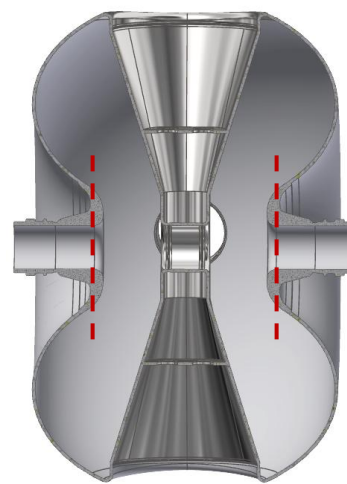
Shell trimming



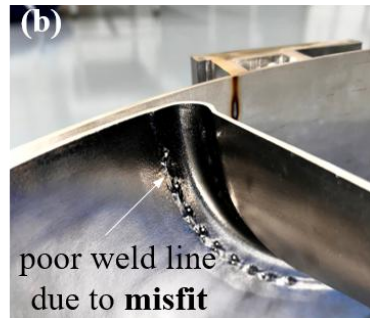
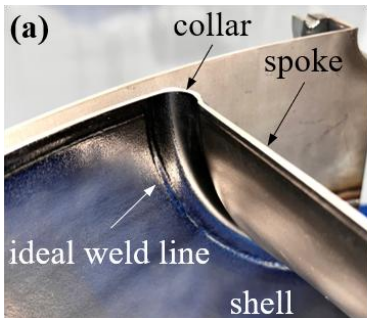
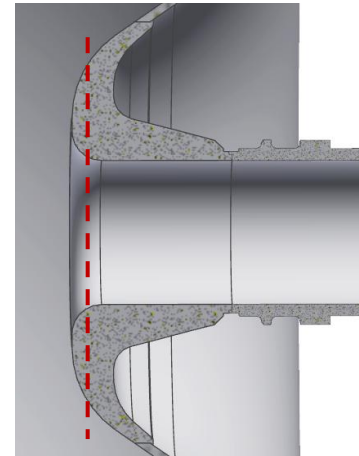
misfit due to shell trimming
→ poor EB welding quality



Beam port cup trimming



trimming



Frequency sensitivity

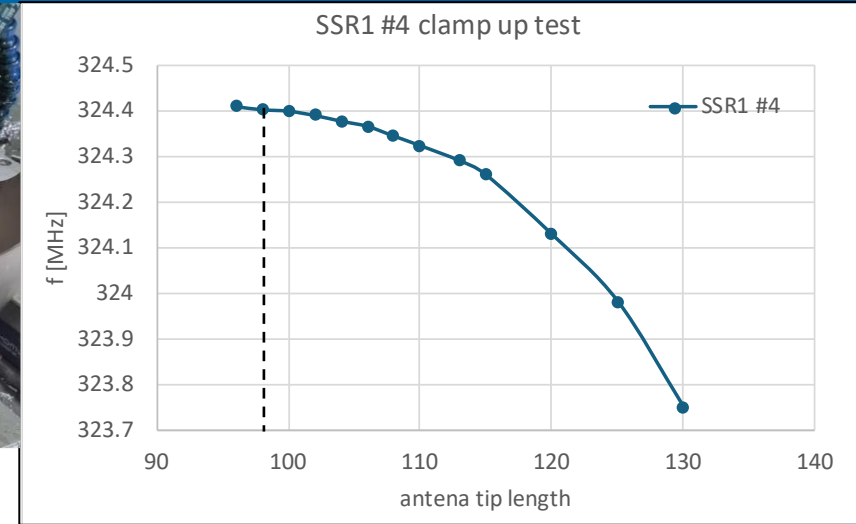
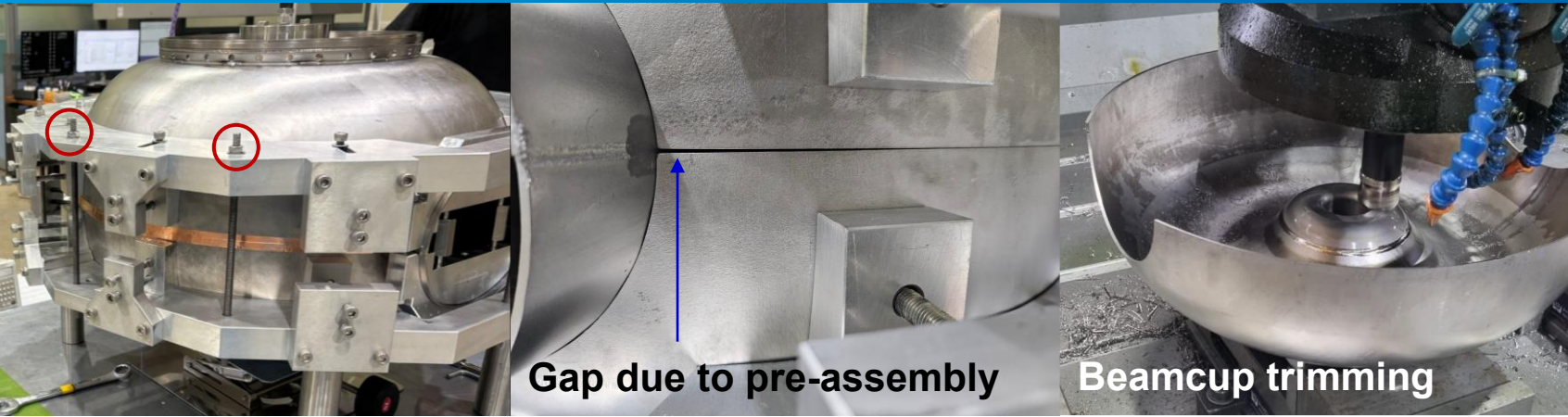
Shell trimming : - 129 kHz/mm

Beamport cup : + 235 kHz/mm (simulation)

+ 233 kHz/mm (#3 cavity)

+ 295 kHz/mm (#2 cavity)

02 고주파 가속관: SSR1, 제작



- Gap occurrence due to pre-assembly of each part
 - Apply copper tape to the gaps (results in frequency increase)
- Determine the optimal tip length by adjusting the pick-up antenna tip length and measuring the frequency
- Frequency variation occurs at each clamp-up due to assembly tolerances
 - With fixed bolt tightening torque, the frequency differs by about 200 kHz
- Trim the beamport cup after frequency measurement

Table. Frequency change during process

process	Δf [MHz]	f [MHz]
Tuner	- 0.07	325.00
2K cooldown	+ 0.84	325.07
vacuum evacuation	+ 0.09	324.23
BCP (150um)	- 0.002	324.14
Spoke - shell welding	+ 0.16	324.14
Spoke - collar welding	+ 0.2	323.98
Half shell welding	- 0.04	323.78
Clamp-up test		323.82

02 고주파 가속관: SSR1, 제작



Beamcup after trimming



Polished inner surface



Inner weld line



outer weld line

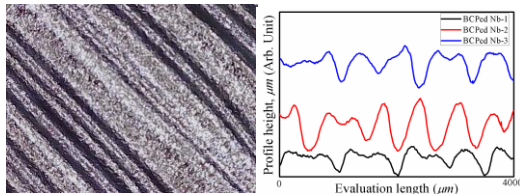
- Clamp-up target frequency 323.8 MHz 달성 후 half shell – shell 용접 진행
- Beamport cup trimming에 따른 용접 전 전체 면 사상 진행

02 고주파 가속관: SSR1, 표면 처리

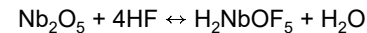
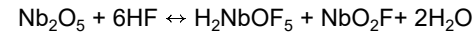
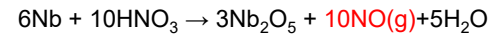
Rotational buffered chemical polishing (BCP)



Bubble streak direction



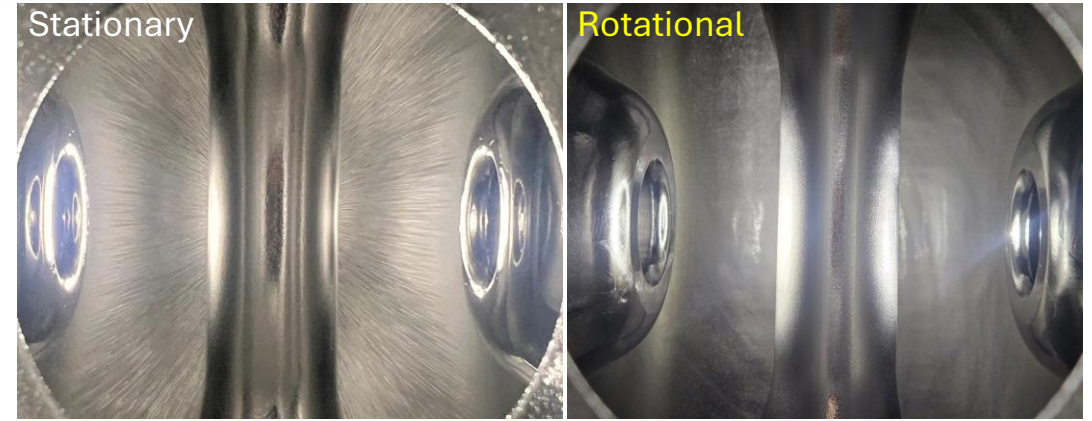
Chemical reaction mechanism



Concept of the improved process

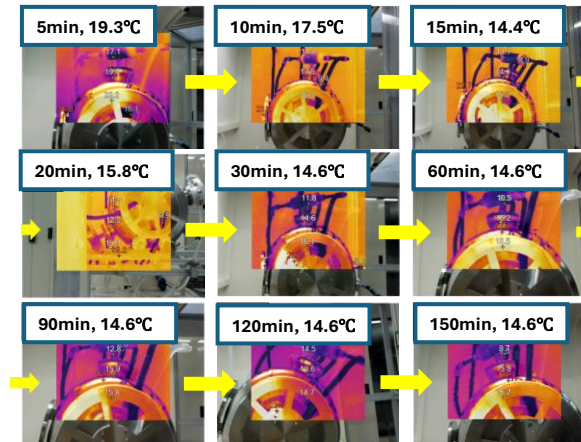
- ✓ NO_x gas bubble adhere to the RF surface, causing bubble streak defects.
- ✓ An approach using **rotational BCP with external cooling circulation** was adopted to mitigate bubble adhesion.
- ✓ This leads to suppressed FE and enhanced quench field.

Visual inspection of RF surface



- No bubble streak observed by visual inspection

Temperature monitoring during BCP process



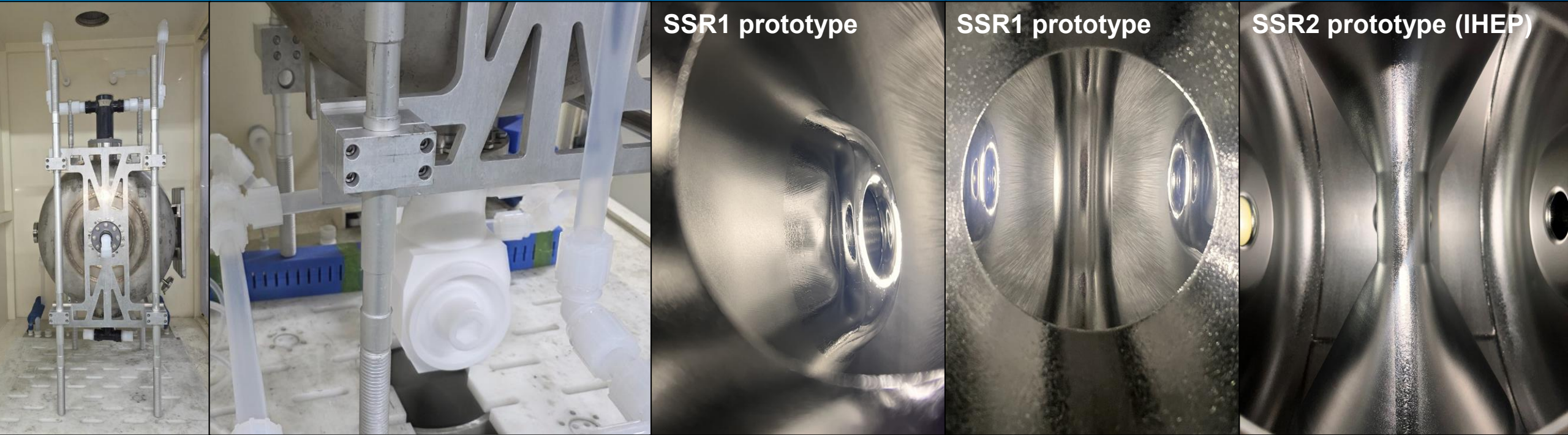
Further consideration

- ✓ Process optimization for uniform etching rate

R-BCP run	1st	2 nd	3rd	4th	5th
Etch rate (μm/min)	1.09	0.78	0.78	0.67	1.78

- ✓ Surface analysis via coupon tests
 - Surface roughness measurement
 - SEM analysis for surface morphology
 - SIMS analysis to examine residual defect along the depth direction
- ✓ **Correlation between surface condition and RF performance** (Q₀, Quench, FE)

02 고주파 가속관: SSR1, 표면 처리



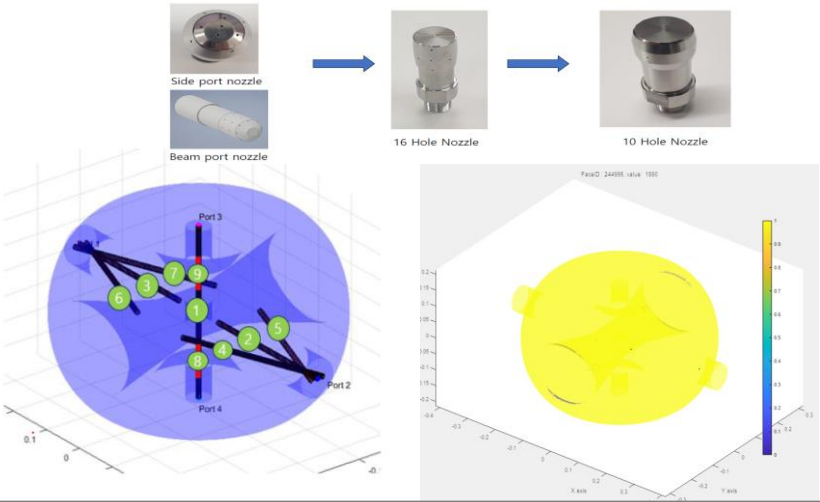
- Bubble streaks are observed in both SSR1 and SSR2 cavities
- A new BCP acid drain system has been introduced to minimize the acid drain time after the BCP process
- HF, HNO₃, H₃PO₄ = 1:1:2, drain time < 15s (decreased from 90s for previous BCP facility)

02 고주파 가속관: SSR1, 고압 수세



High pressure rinsing (HPR)

Nozzle & HPR coverage simulation



Further consideration

- Introduction of an external cleaning process
- Optimization of nozzle angle, position and rotational speed for maximum HPR coverage
- Correlation with RF performance (field emission)



Qualification of ultra pure water

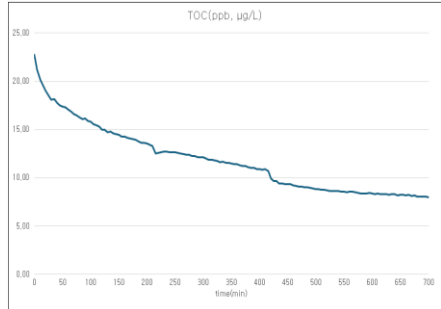
✓ Target of ultra pure water

Time (m)	Unit	Target
Resistivity	M/cm @25°C	> 17.5
Particles	ea/ml under 0.5 mm dia.	10~20
TOC (total organic carbon)	Ppb	< 10
D.O.	Ppb	< 50

✓ Liquid particle measurement

Datetime (Y-Axis)	0.1 μm	0.15 μm	0.2 μm	0.3 μm	0.5 μm
2026-01-14 10:56	47	30	24	13	10
2026-01-14 13:39	55	33	22	6	2
2026-01-14 13:40	56	31	19	4	2
2026-01-14 14:13	55	30	19	7	1
2026-01-14 14:25	54	31	19	5	0
2026-01-14 14:30	63	32	23	4	0
2026-01-14 14:34	74	42	24	7	2
2026-01-14 14:37	70	36	21	3	1
2026-01-14 14:39	62	37	29	7	1
2026-01-14 14:41	60	26	19	1	1

✓ TOC tracking after changing UV filter

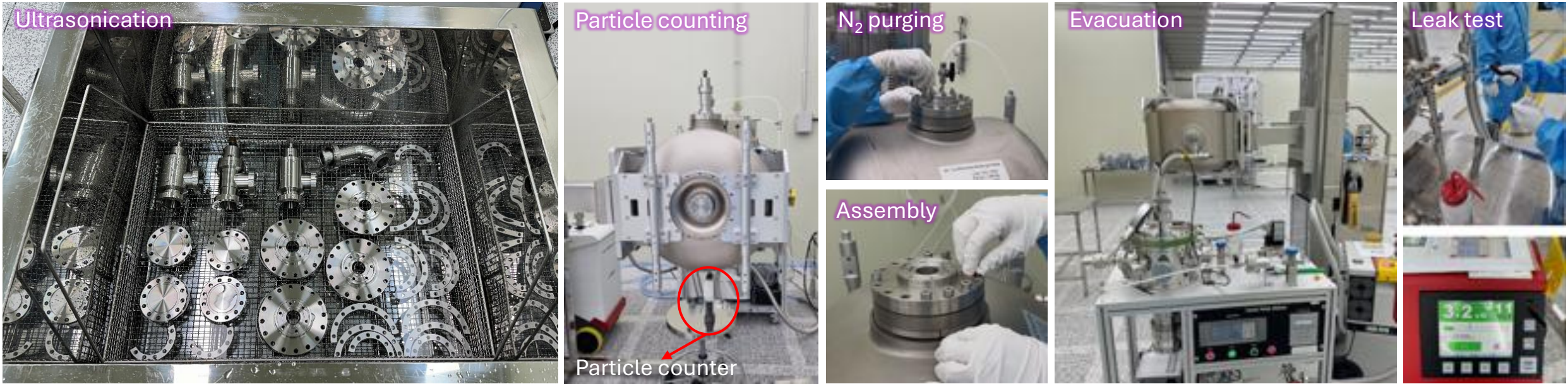


Time (min)	TOC (ppb, mg/L)
10	22.75
12	14.96
14	12.68
16	11.54
18	9.04
20	7.99

02 고주파 가속관: SSR1, 청정 조립



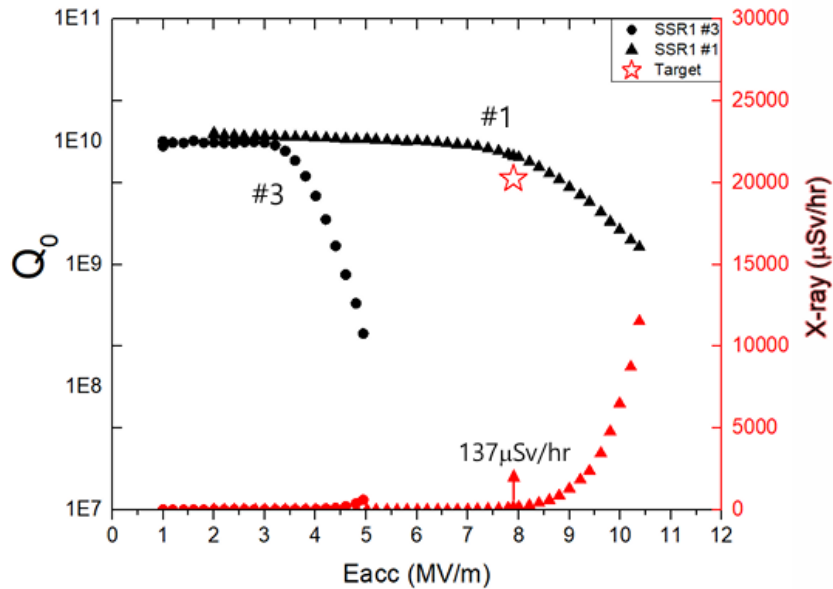
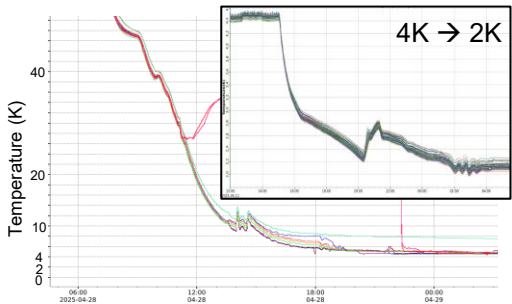
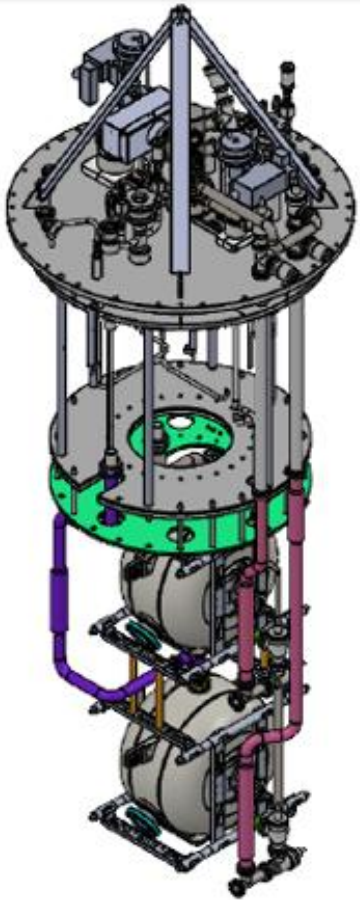
Clean assembly



- All vacuum components used in clean assembly are cleaned by ultrasonic cleaning and ionized air blowing to remove contaminants prior to use.
- During assembly, particle levels are continuously monitored, and the process proceeds to the next step only when the particle count reaches zero.
- During evacuation, a slow pumping step is adopted to suppress particle migration and ensure stable particle conditions.



Vertical test



Parameters	Value
Temperature [K]	2
Q_0 at 1MV/m	1.01E+10
R_{res} (n Ω)	9.1
Q_0 at 8.5 MV/m	-
X-ray onset	3.4
LFD (Hz/(MV/m) ²)	-8.1
df/dp (Hz/mbar)	-31.1
Q_c	6.76E+10
Q_t	3.03E+11
Multipacting band (MV/m)	0.44 – 0.55

- SSR1 cavity tested in vertical cryostat
- Magnetic shielding applied to reduce ambient (earth) magnetic field and minimize trapped flux

끝

